

# References

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# Preface

Notes on CMOS Integrated Circuits & VLSI.

# Resources

Some relevant resources:

- EECS 312 - University of Michigan
- EECS 427 - University of Michigan
- [CMOS VLSI Design Web Supplements](#)
  - Contains supplemental materials e.g. lecture slides, figures, solutions, code, etc
- [Digital VLSI Chip Design with Cadence and Synopsys CAD Tools](#)
- [VLSI Universe](#)

Textbooks:

- J. Rabaey, A. Chandrakasan, and B. Nikolic. Digital Integrated Circuits A Design Perspective, Edition: 2. Alexandria, VA: Prentice Hall, 2003
- CMOS VLSI Design: A Circuits and Systems Perspective 4th Edition

# 1 Introduction

## 1.1 Perspective

**i** Note 1: Definition - Some definition

**Term** is defined as blah blah blah...

This note does ...

## 1.2 High Level Ideas



## 2 Circuit Basics

A brief review of the fundamental concepts of electrical circuits that form the foundation for understanding CMOS and VLSI design.

### 2.1 Important Constants

Constant	Symbol	Value	Units
Elementary Charge	$e$	$1.602 \times 10^{-19}$	C
Boltzmann Constant	$k_B$	$1.380 \times 10^{-23}$	J/K
Room Temperature	$T$	300	K
Thermal Voltage at 300K	$V_T$	25.9	mV
Silicon Bandgap	$E_g$	1.12	eV
Permittivity of Free Space	$\epsilon_0$	$8.854 \times 10^{-12}$	F/m
Silicon Relative Permittivity	$\epsilon_r$	11.7	-
Silicon Oxide Relative Permittivity	$\epsilon_{ox}$	3.9	-

### 2.2 Common Unit Conversions

From	To	Conversion
eV	Joules	$1 \text{ eV} = 1.602 \times 10^{-19} \text{ J}$
Temperature	Thermal Voltage	$V_T = \frac{k_B T}{q}$
Frequency	Time Period	$T = \frac{1}{f}$
Resistance $\times$ Capacitance	Time Constant	$\tau = RC$

## 2.3 Charge, Voltage, Current, Power

### 2.3.1 Charge (Q)

Electric charge is measured in Coulombs (C). The fundamental unit of charge is the electron charge:

$$Q_e = -1.602 \times 10^{-19} \text{ C}$$

The movement of charge carriers (typically electrons in circuits) creates current.

### 2.3.2 Voltage (V)

Voltage is the electric potential difference between two points, measured in Volts (V). Key equations:

$$V = IR \text{ (Ohm's Law)}$$

$$V = \frac{dW}{dQ} \text{ (Work per unit charge)}$$

### 2.3.3 Current (I)

Current is the rate of charge flow, measured in Amperes (A):

$$I = \frac{dQ}{dt}$$

For sinusoidal signals:

$$I = I_0 \sin(\omega t)$$

### 2.3.4 Power (P)

Power is the rate of energy transfer, measured in Watts (W):

$$P = VI \text{ (instantaneous)}$$

$$P = I^2 R \text{ (resistive loss)}$$

$$P = CV^2 f \text{ (dynamic CMOS)}$$

$$P_{avg} = \frac{1}{T} \int_0^T p(t) dt \text{ (average)}$$

## 2.4 Resistance, Capacitance, Inductance

### 2.4.1 Resistance (R)

Resistance is the property of a material that opposes the flow of electric current, resulting in the conversion of electrical energy to thermal energy.

Key equations:

$$V = IR \text{ (Ohm's Law)}$$

$$P = I^2 R \text{ (power dissipation)}$$

$$R = \rho \frac{L}{A} \text{ (bulk resistance)}$$

where:

- $\rho$  is resistivity
- $L$  is length
- $A$  is cross-sectional area

### 2.4.2 Capacitance (C)

Capacitance (measured in Farads F) is the ability of a component to store electric charge, measured as the ratio of stored charge to the applied voltage. Key equations:

$$\begin{aligned}Q &= CV \text{ (charge stored)} \\I_C &= C \frac{dV}{dt} \text{ (capacitor current)} \\ \tau &= RC \text{ (time constant)}\end{aligned}$$

For parallel plate capacitors:

$$C = \frac{\epsilon_0 \epsilon_r A}{d}$$

where: -  $A$  is plate area -  $d$  is plate separation -  $\epsilon_0$  is permittivity of free space -  $\epsilon_r$  is relative permittivity

### 2.4.3 Inductance (L)

Inductance (measured in Henries H) is the property of a circuit element to oppose changes in current flow by storing energy in a magnetic field:

$$\begin{aligned}V_L &= L \frac{dI}{dt} \\ \tau_L &= \frac{L}{R} \text{ (inductive time constant)} \\ E &= \frac{1}{2} LI^2 \text{ (stored energy)}\end{aligned}$$

## 2.5 Electric Fields

An electric field is a region of space surrounding a charged particle where another charged particle would experience a force, essentially acting like an invisible “push” or “pull” depending on the charges involved. It is the **force per unit charge** experienced by a small positive test charge placed at that point. Units:  $V/m$  or  $N/C$

$$E = \frac{F}{q}$$

- 
- electric field is the rate of change of voltage w.r.t. position

- strong electric field -> rapid change in voltage over short distance
- In circuits, voltage sources create electric fields that drive current flow

## 2.6 KVL & KCL

### 2.6.1 Kirchhoff's Voltage Law (KVL)

The sum of voltages around any closed loop equals zero:

$$\sum_{k=1}^n V_k = 0$$

### 2.6.2 Kirchhoff's Current Law (KCL)

The sum of currents entering a node equals the sum of currents leaving it:

$$\sum I_{in} = \sum I_{out}$$

$$\sum_{k=1}^n I_k = 0 \text{ (node equation)}$$

## 2.7 Basic Circuit Configurations

### 2.7.1 Series Connections

In series connections, components share the same current:

$$I_{total} = I_1 = I_2 = \dots = I_n$$

For components in series:

- Resistors:  $R_{total} = R_1 + R_2 + \dots + R_n$
- Capacitors:  $\frac{1}{C_{total}} = \frac{1}{C_1} + \frac{1}{C_2} + \dots + \frac{1}{C_n}$
- Inductors:  $L_{total} = L_1 + L_2 + \dots + L_n$
- Voltage Division:  $V_i = V_{total} \frac{R_i}{R_{total}}$

### 2.7.2 Parallel Connections

In parallel connections, components share the same voltage:

$$V_{total} = V_1 = V_2 = \dots = V_n$$

For components in parallel:

- Resistors:  $\frac{1}{R_{total}} = \frac{1}{R_1} + \frac{1}{R_2} + \dots + \frac{1}{R_n}$
- Capacitors:  $C_{total} = C_1 + C_2 + \dots + C_n$
- Inductors:  $\frac{1}{L_{total}} = \frac{1}{L_1} + \frac{1}{L_2} + \dots + \frac{1}{L_n}$
- Current Division:  $I_i = I_{total} \frac{R_{total}}{R_i}$

## 2.8 Capacitor

A capacitor stores electrical energy in an electric field created between two conductive plates separated by an insulator (dielectric)

- When a voltage is applied, electrons build up on one plate (creating negative charge), and the other plate loses electrons (resulting in positive charge)
- 

## 2.9 Additional Topics Relevant to CMOS/VLSI

### 2.9.1 Small Signal Analysis

Key parameters and equations:

$$g_m = \frac{\partial I_D}{\partial V_{GS}} \text{ (transconductance)}$$

$$r_o = \frac{\partial V_{DS}}{\partial I_D} \text{ (output resistance)}$$

$$A_v = -g_m r_o \text{ (small-signal gain)}$$

## 2.9.2 RC Networks

Time domain analysis:

$$v(t) = V(1 - e^{-t/RC}) \text{ (charging)}$$

$$v(t) = Ve^{-t/RC} \text{ (discharging)}$$

$$t_p \approx 0.69RC \text{ (propagation delay)}$$

## 2.9.3 Noise and Signal Integrity

Thermal noise power spectral density:

$$S_v(f) = 4k_BTR \text{ (V}^2/\text{Hz)}$$

Shot noise current spectral density:

$$S_i(f) = 2qI_D \text{ (A}^2/\text{Hz)}$$

Signal-to-Noise Ratio:

$$SNR = \frac{P_{signal}}{P_{noise}} = \frac{V_{signal,rms}^2}{V_{noise,rms}^2}$$

## 2.9.4 Semiconductor Physics Basics

Carrier concentration:

$$n_i^2 = N_C N_V e^{-E_g/k_B T}$$

Built-in potential:

$$V_{bi} = V_T \ln\left(\frac{N_A N_D}{n_i^2}\right)$$

MOSFET threshold voltage:

$$V_{th} = V_{FB} + 2\phi_F + \frac{\sqrt{2\epsilon_s q N_A (2\phi_F)}}{C_{ox}}$$

where:

- $V_{FB}$  is the flatband voltage
- $\phi_F$  is the Fermi potential
- $N_A$  is acceptor concentration
- $C_{ox}$  is oxide capacitance per unit area

## 2.10 PN Junctions

The PN junction is fundamental to semiconductor devices and CMOS operation. Key concepts and equations:

### 2.10.1 Built-in Potential

The built-in potential ( $V_{bi}$ ) across the junction at equilibrium:

$$V_{bi} = V_T \ln\left(\frac{N_A N_D}{n_i^2}\right)$$

where:

- $N_A$  is acceptor concentration in p-region
- $N_D$  is donor concentration in n-region
- $n_i$  is intrinsic carrier concentration
- $V_T$  is thermal voltage ( $k_B T/q$ )

### 2.10.2 Depletion Region

The depletion width ( $W$ ) under bias:

$$W = \sqrt{\frac{2\epsilon_s}{q} \left(\frac{N_A + N_D}{N_A N_D}\right) (V_{bi} - V_A)}$$

where:

- $V_A$  is the applied voltage
- $\epsilon_s$  is semiconductor permittivity
- $q$  is elementary charge

### 2.10.3 Current-Voltage Relationship

The ideal diode equation:

$$I_D = I_S (e^{V_D/V_T} - 1)$$

where:

- $I_S$  is the reverse saturation current
- $V_D$  is the diode voltage
- $V_T$  is thermal voltage



The saturation current:

$$I_S = qA\left(\frac{D_p}{L_p}p_n + \frac{D_n}{L_n}n_p\right)$$

where:

- $D_p, D_n$  are diffusion coefficients
- $L_p, L_n$  are diffusion lengths
- $A$  is junction area

#### 2.10.4 Junction Capacitance

The junction capacitance has two components:

**Depletion capacitance:**

$$C_j = \frac{C_{j0}}{\sqrt{1 - V_D/V_{bi}}}$$

**Diffusion capacitance:**

$$C_d = \tau_T \frac{dI_D}{dV_D} = \tau_T \frac{I_D + I_S}{V_T}$$

where:

- $C_{j0}$  is zero-bias junction capacitance
- $\tau_T$  is transit time

#### 2.10.5 Temperature Effects

Temperature dependence of key parameters:

$$I_S(T) \propto T^3 e^{-E_g/k_B T}$$

$$V_{bi}(T) = V_{bi}(T_0) - \beta(T - T_0)$$

where  $\beta$  is the temperature coefficient.

### 2.11 Note

#### **i** Note on Temperature Dependencies

Many parameters in CMOS circuits have significant temperature dependencies. Key relationships include:

- Mobility:  $\mu(T) \propto T^{-3/2}$

- Threshold voltage:  $V_{th}(T) = V_{th}(T_0) + \alpha(T - T_0)$
- Leakage current:  $I_{leak} \propto T^2 e^{-E_g/2k_B T}$

## 3 High-level Overview

### 3.1 MOS Transistors

Silicon Lattice

PN Junction

NMOS PMOS



## **3.2 CMOS Logic**

### **3.2.1 Pass Transistors, Transmission Gates**

### **3.2.2 Tristates**

### **3.2.3 Multiplexers**

## **3.3 Sequential Circuits**

### **3.3.1 Latches**

### **3.3.2 Flip-Flops**

## **3.4 Fabrication & Layout**

### **3.4.1 Fabrication Process**

### **3.4.2 Layout Design Rules**

#### **3.4.2.1 Gate Layout**

#### **3.4.2.2 Stick Diagrams**

## **3.5 Design Partitioning**

## **3.6 Architecture**

## **3.7 Logic Design**

## **3.8 Circuit Design**

## **3.9 Physical Design**

## **3.10 Design Verification**

## **3.11 Fabrication, Packaging, and Testing**

# 4 CMOS Basics

## 4.1 MOS Transistor Basics

### 4.1.1 Silicon Lattice

#### Silicon (Si)

- semiconductor, forms basic starting material
- A Group IV element -> forms covalent bonds with 4 adjacent atoms
  - with **pure silicon**, all valence electrons are in chemical bonds, thus a **poor conductor**
- Raise conductivity adding **dopants** into the lattice (adding impurities)
- Dopant from Group V (e.g. arsenic As) has 5 valence electrons
  - Replacing one silicon atom leads to the lattice having 4 bonds but 1 valence electron loosely bound (b in fig. below)
  - Free electron can carry current thus raising conductivity
  - This is an **n-type** semiconductor
    - \* Free **carriers** are **negatively charged electrons**
- Dopant from Group III (e.g. boron B) has 3 valence electrons
  - Similarly, boron atom can borrow electron from neighboring Si which is now short by one electron
    - \* This creates a **hole** (a missing electron)
    - \* hole acts as positive carrier
  - This is a **p-type** semiconductor (c in fig. below)
- Note that when current flows, electrons and holes move in **opposite directions**
  - Recall how electrons move opposite to direction of conventional current flow
    - \* Holes move in same direction as conventional current flow
    - \* in semiconductors, current can be carried by holes as well because both electrons and holes are primary charge carriers
      - This goes into band structure of semiconductors:

- Electrons occupy two main energy bands: **valence band** (lower energy) and **conduction band** (higher)
- When an electron gains enough energy (eg through doping) it moves from valence to conduction band, leaving a hole in valence band
- p-type doping creates deficit of electrons in valence band (creating holes)

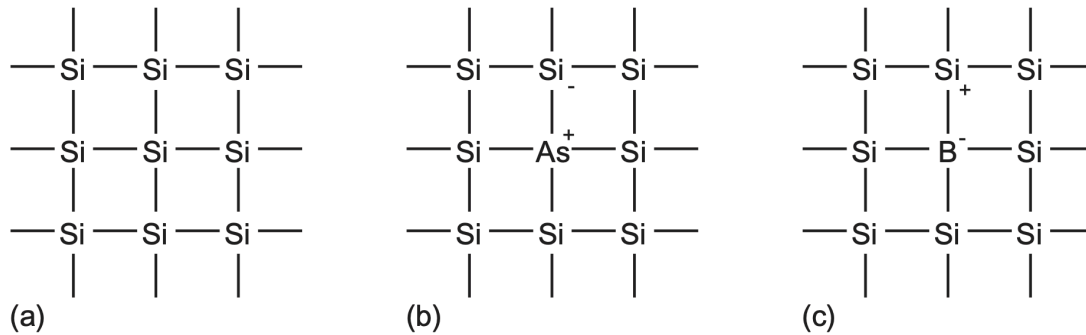


Figure 4.1: Silicon lattice shown as 2D plane for simplicity (but is actually 3D cubic crystal).  
Source: (Weste and Harris 2010)

#### 4.1.2 PN Junction

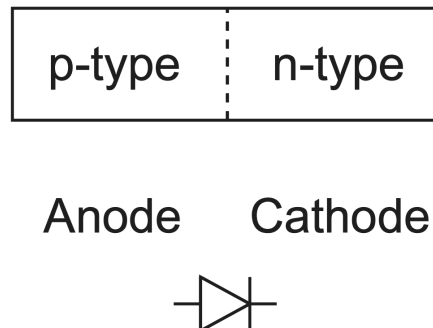


Figure 4.2: PN Junction. Source: (Weste and Harris 2010)

Junction between p-type (anode) and n-type (cathode) is a **diode**

- Voltage on p-type  $>$  n-type: diode is **forward biased** and current flows
- Otherwise (p-type  $\leq$  n-type): diode is **reverse biased**, very little current flows

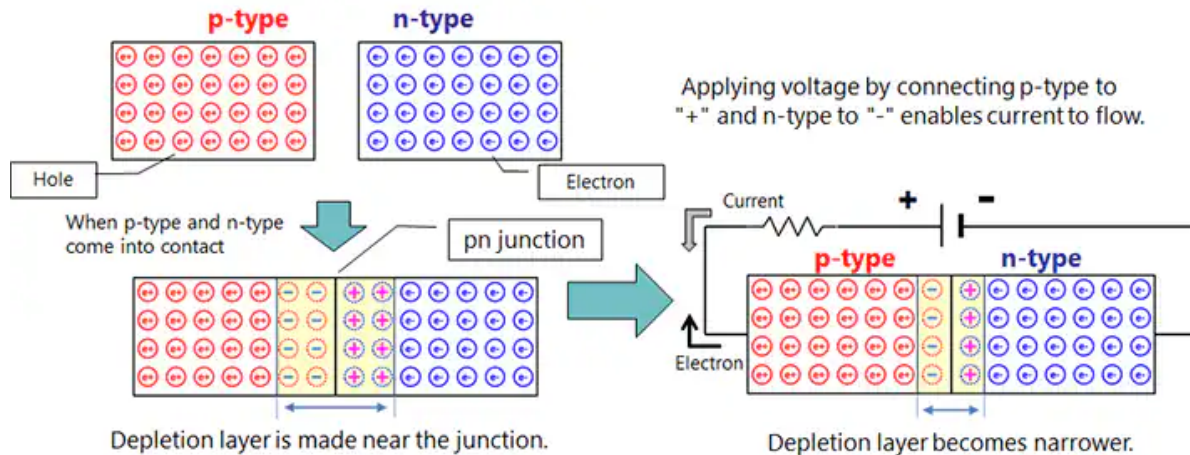


Figure 4.3: [Source](#)

- charge transfer (of electrons and holes) across the junction is called **diffusion**
- free electrons in the anode fills up some holes in the cathode
- this forms a **depletion layer**
  - depletion layer is depleted of any free carriers (electrons or holes)
    - \* in comparison on the n- and p-regions there are still free carriers
  - acts as a barrier to further current flow
- When applying **forward bias** (anode has higher voltage)
  - Positive voltage on p-type pushes holes towards junction
  - Negative voltage on n-type pushes electrons towards junction (where negative ions are repelling )
  - Shrinks depletion region
    - \* Once voltage is high enough, depletion region becomes so thin that electrons can freely pass (current flow)
- When applying **reverse bias** (anode has lower voltage)
  - Negative voltage on p-type pulls holes away from junction
  - Positive voltage on n-type pulls electrons away from junction
  - Makes depletion region wider
    - \* Creates stronger barrier to current flow

Analogy: A hill between two valleys. Forward bias reduces height of the hill, making it easy for charges to cross the hill. Reverse bias makes the hill taller, making it more difficult.

**Why does the depletion region create a barrier? Why don't more electrons cross into p-type to fill up holes?**



- When an electron fills a hole in the p-type
  - leaves behind positive ion on n-type (an atom lost its extra electron)
  - leaves behind a negative ion on the p-type (an atom has an extra electron)
- Thus depletion region becomes filled with positive ions on n-type side and negative ions on p-type side
  - Recall that ions are charged particles - (i.e. has more electrons than protons, or more protons than electrons)
- **Ions create an electric field**
  - (+) ions in the n-side and (-) ions in the p-side create an electric field pointing from n to p
    - \* electric field opposes the further flow of electrons
    - \* Think of like building static electricity: more charge separates, the stronger the opposing force becomes

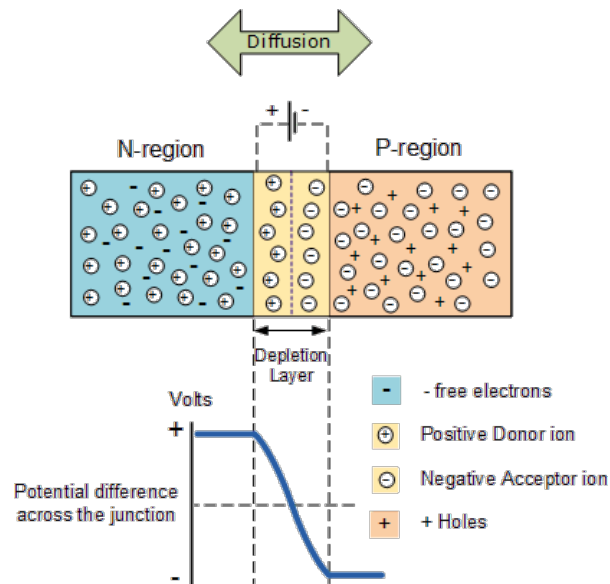


Figure 4.4: [Source](#)

### 4.1.3 Transistor Structure

Terminology clarifications:

- Metal-Oxide Semiconductor (MOS) - refers to the structure used in MOSFETs (ie consisting of the M, O, and S)

- Metal-Oxide Semiconductor Field-Effect Transistor (MOSFET) - the actual type of FET that uses MOS structure for a transistor
- Field-Effect Transistors (FET) - superset of MOSFET - transistors that control current using an electric field
  - Voltage-controlled device
  - Sometimes used interchangeably with MOSFET
- Complementary Metal-Oxide Semiconductor (CMOS) - refers to the technology that use both NMOS and PMOS (complementary)
  - Why CMOS?
    - \* In steady-state, only one type of transistor (N or PMOS) conducts
      - Thus no direct current path from supply to ground, leading to lower static power
      - i.e. power mainly comes from switching (although see further notes on static power)
    - \* Full rail-to-rail swing (0 to VDD) - good logic level separation
  - E.g. compared to pure NMOS logic, CMOS has lower static power dissipation and full voltage swing (but slower)

FET because transistor operation is controlled by electric fields (thus the *field effect* transistor)

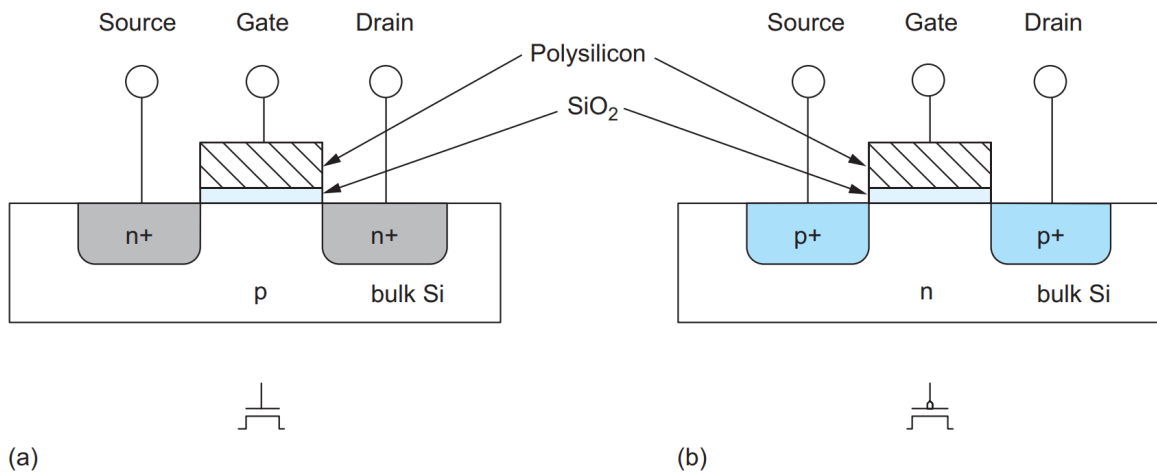


Figure 4.5: Cross-sections of a) nMOS, and b) pMOS. n+/p+ regions are heavily doped.  
Source: (Weste and Harris 2010)

CMOS technology provides two types of transistors/devices: **n-type transistor (nMOS)**, and **p-type transistor (pMOS)**

## MOS Structure:

- **gate** - conducting gate
  - Early transistors: metal gates
  - 1970s and on: **polysilicon** (polycrystalline silicon)
  - metal gates have reemerged in '07
- **silicon dioxide** ( $\text{SiO}_2$ , glass)
  - Essentially works as the dielectric (insulator) between gate and semiconductor
- **substrate/body/bulk** - the silicon wafer
- NMOS is built with p-type body, with n-type semiconductor adjacent to the gate. These regions are the **source** and the **drain**. The body is typically grounded.
  - PMOS is opposite
- The substrate is either n-type or p-type, with the other flavor of transistor built in a special **well** to form the body of the opposite type
- **gate** is the control input - affecting flow of electrical current between source and drain

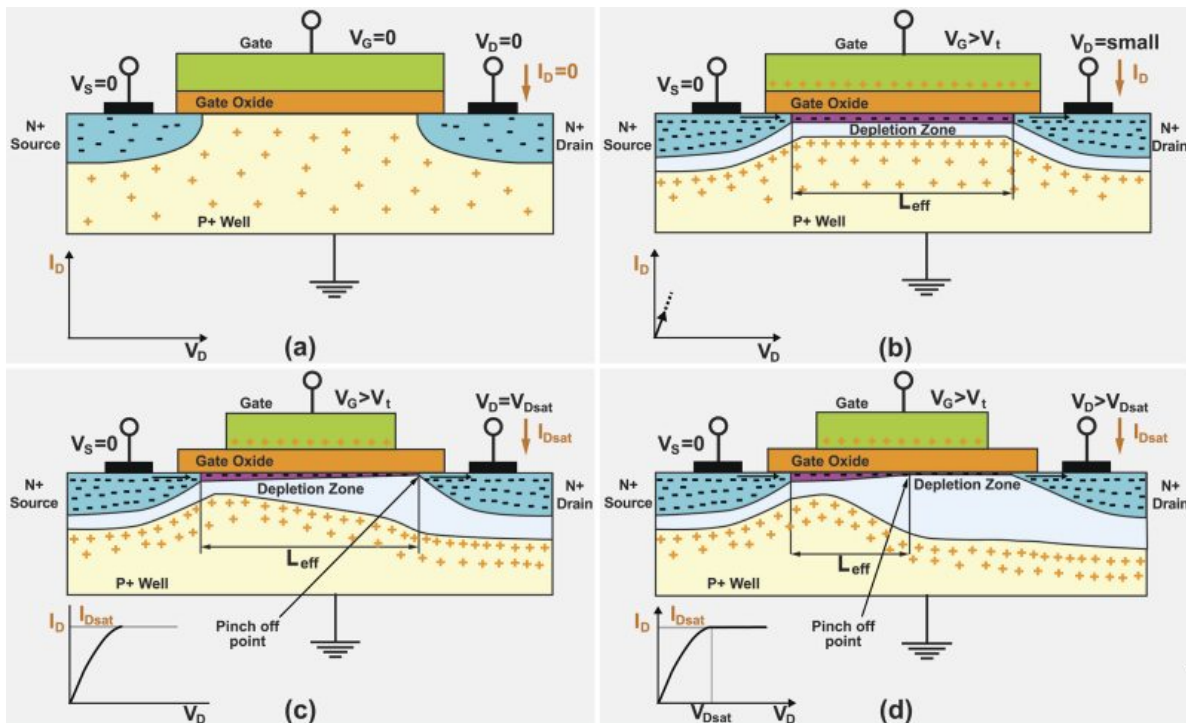


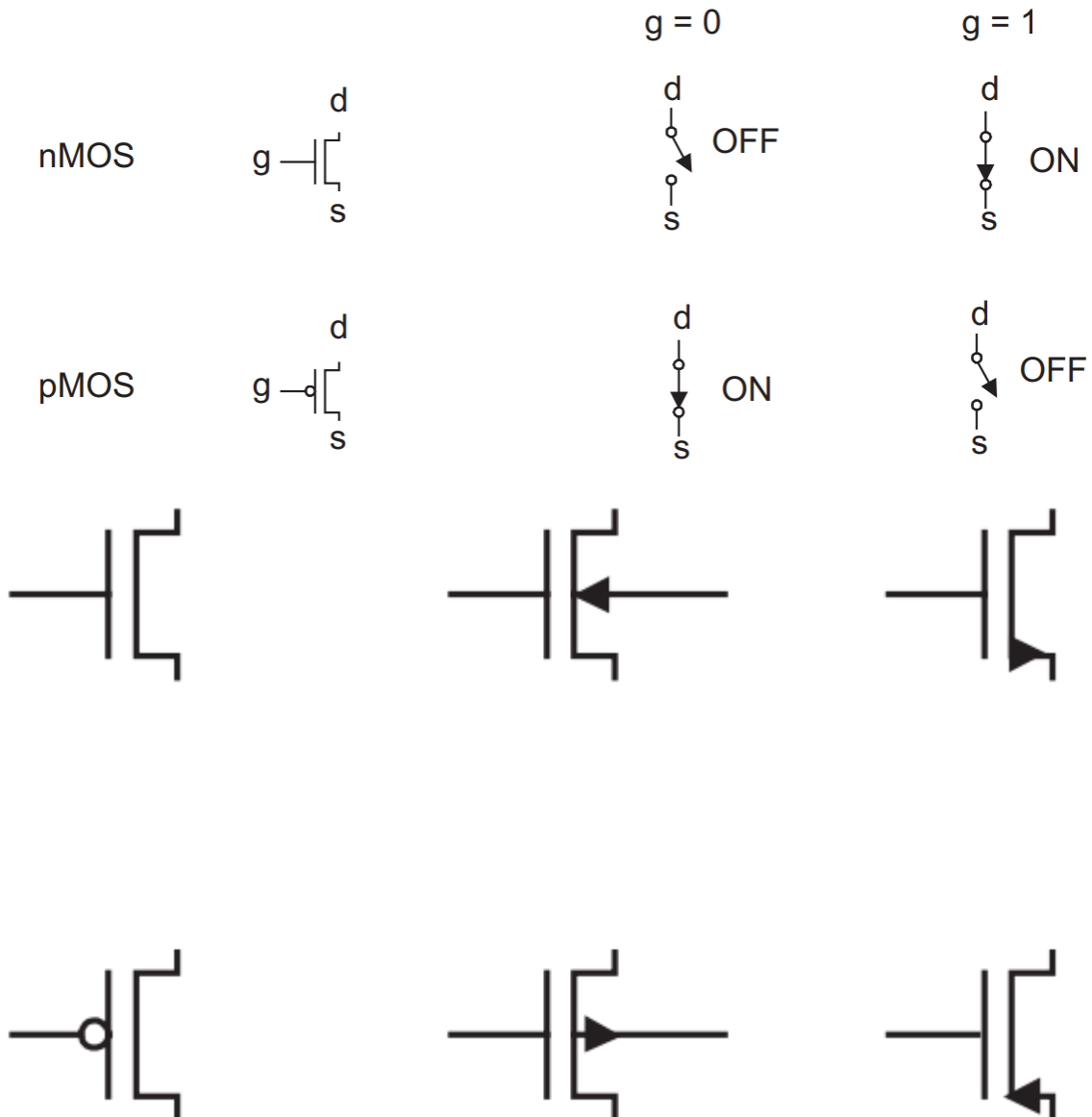
Figure 4.6: NMOS Operations. [Source](#)

## NMOS:

- body is grounded (pn junction of source and drain to body is reverse-biased)
  - If gate is also grounded, no current can flow through the junctions since they are reverse-biased
    - \* Thus transistor is OFF
  - As gate voltage is raised, gate creates electric field that attracts free electrons
    - \* Why does raising gate voltage attract free electrons?
      - MOS structure essentially creates a parallel-plate capacitor (gate as a plate, and silicon beneath SiO<sub>2</sub> as a plate)
      - Gate voltage (potential difference) between the two plates create an electric field
      - Since SiO<sub>2</sub> is an insulator, charge cannot flow through it, thus inducing charge redistribution in the semiconductor
      - Positive gate voltage -> “capacitor” of gate and substrate forms electric field pointing downwards, pulling electrons upwards (positive potential of gate attracts them)
  - Once voltage is raised enough, electrons outnumber holes and creates a **channel**
    - \* **channel** is the thin region under the gate that becomes inverted to act as an n-type semiconductor
      - allowing conducting path of electron flow between source and drain
      - Thus transistor is ON

## PMOS:

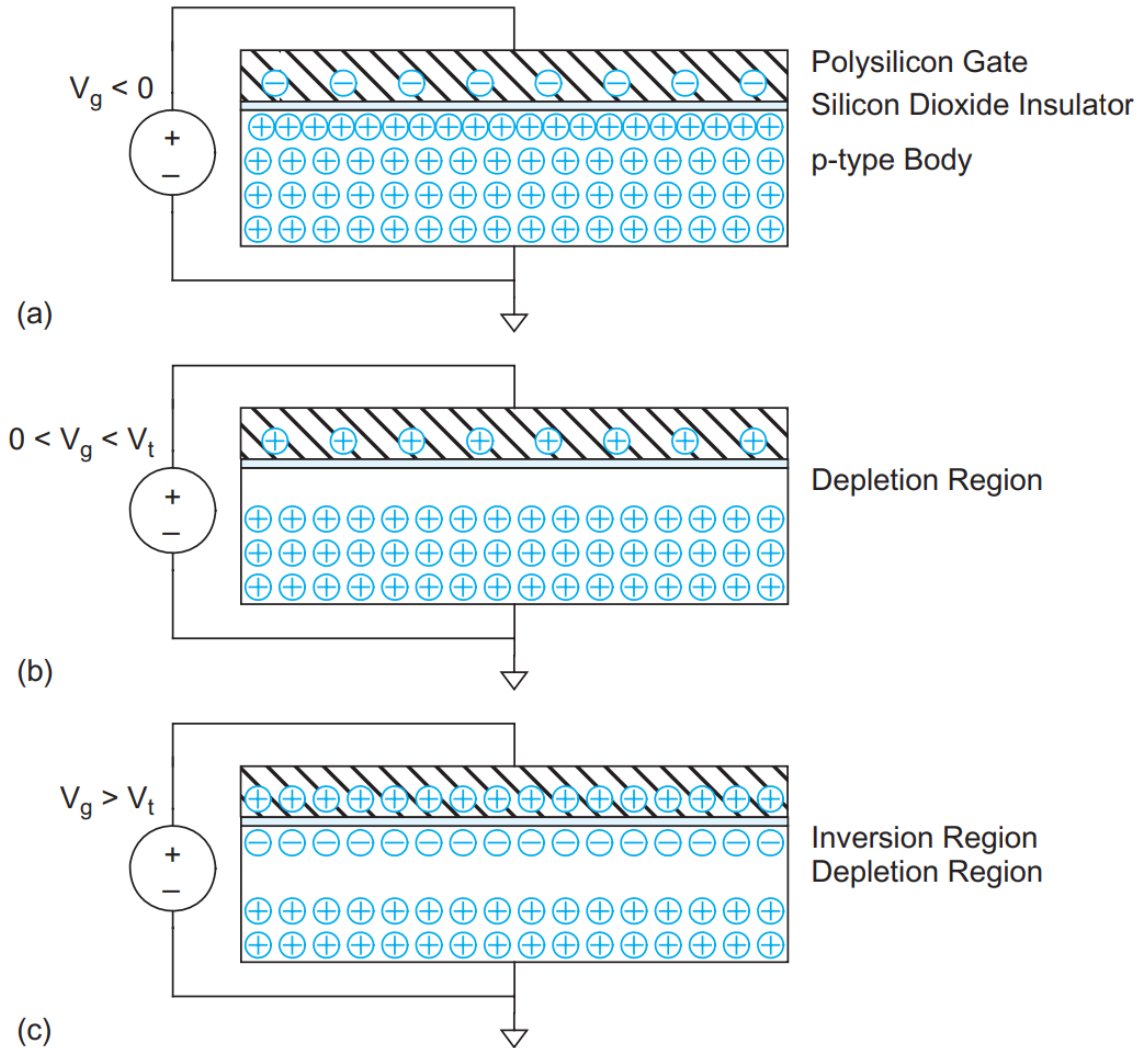
- Situation is opposite: body is at positive voltage
  - When gate is at positive voltage, source and drain junctions are reverse-biased -> no current flow
  - At lowered gate voltage, positive charges attracted towards the bottom of the SiO<sub>2</sub>
    - \* Low enough gate voltage inverts the channel creating a conducting path for positive carriers from source to drain
- High voltage (Logic level 1) usually denoted  $V_{DD}$  or POWER
  - VDD for Voltage Drain Drain
- Low voltage (Logic level 0) called GROUND (GND) or denoted as  $V_{SS}$ 
  - VSS for Voltage Source Source
- This allows MOSFETs to be viewed as ON/OFF switches



- The MOS transistor is a **majority-carrier** device - gate voltage controls current in a conducting channel between source and drain
  - NMOS: majority carriers are electrons
  - PMOS: majority carriers are holes
- Note that the source terminal sources the majority carrier which go to the drain
  - i.e. for nmos electrons go from source to drain, for pmos holes go

#### 4.1.4 Very Simplified Model

The following demonstrates a very simplified MOS without the source and drain:



**FIGURE 2.2** MOS structure demonstrating (a) accumulation, (b) depletion, and (c) inversion

Figure 4.7: Source:(Weste and Harris 2010)

- a) negative voltage on gate - holes attracted to region beneath the gate
- b) small positive voltage on gate - some positive charge on the gate, repelling the like holes below the gate

- **depletion** region - region in the body where holes are repelled away
- c) higher positive potential larger than a threshold voltage  $V_t$  on gate - attracts a lot of positive charge to the gate, further repelling the holes and some free electrons in the body are attracted to the region beneath the gate
- **inversion** layer - the conductive layer of electrons in the p-type body

Now let us examine an NMOS:

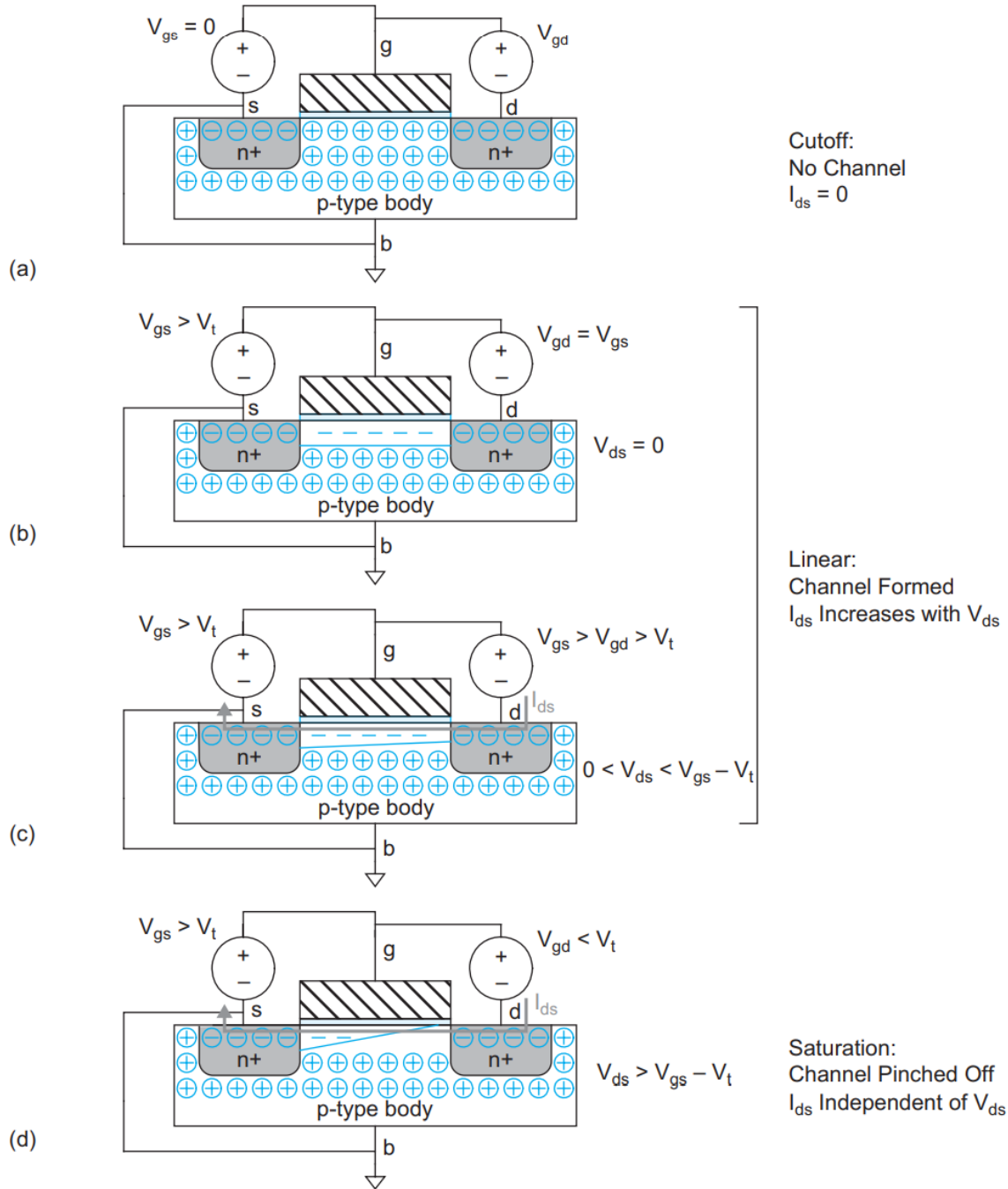


Figure 4.8: NMOS Regions of Operation: a) Cutoff region b, c) Linear region d) Saturation region Source: (Weste and Harris 2010)



### Cutoff Region:

- $V_{gs} < V_t$
- Source and drain have free electrons, body has free holes but no free electrons
  - junction between body and source/drain are zero/reverse-biased, so little to no current flow
  - OFF
- 

### Linear Region:

- aka resistive, triode, nonsaturated, unsaturated, ohmic
- $V_{gs} > V_t$ 
  - but  $0 < V_{ds} < V_{gs} - V_t$
- Inversion region of majority carriers (in this case electrons) - named the **channel** - creates a conductive path between source and drain
- ON
- Number of carriers and conductivity increases with gate voltage
- **Potential difference between drain and source:**  $V_{ds} = V_{gs} - V_{gd}$ 
  - if  $V_{ds}$  is 0, no electric field to push current from drain to source
- When small positive  $V_{ds}$  - current  $I_{ds}$  flows from drain to source
  - The current increases with both  $V_{ds}$  and  $V_{gs}$

### Saturation Region:

- $V_{ds}$  is so large that  $V_{gd} < V_t$
- channel is no longer inverted and is **pinched off**

Analogy: water valve

- Gate is the valve of a water pipe

## **4.2 Long-Channel I-V Characteristics**

## **4.3 C-V Characteristics**

## **4.4 Nonideal I-V Effects**

## **4.5 DC Transfer Characteristics**

## **4.6 Resources / References**

Videos:

- [CircuitBread - MOSFET](#)
- [CircuitBread - FET Regions of Operation](#)

## **5 CMOS Fabrication & Process Technology**

## 6 CMOS Capacitance

## **7 Inverters and More Gates**

## 8 Delay

## 9 Power

## 10 Interconnect



# 11 Robustness

## 12 Circuit Simulation

# 13 Combinational Circuit Design

Ref (cmosvlsi-4th?)

## 14 Sequential Circuit Design

## **15 Datapath Subsystems**

## **16 Array Subsystems**

## **17 Special-Purpose Subsystems**

## **18 Design Methodology and Tools**



## **19 Testing, Debugging, and Verification**

## 20 Summary

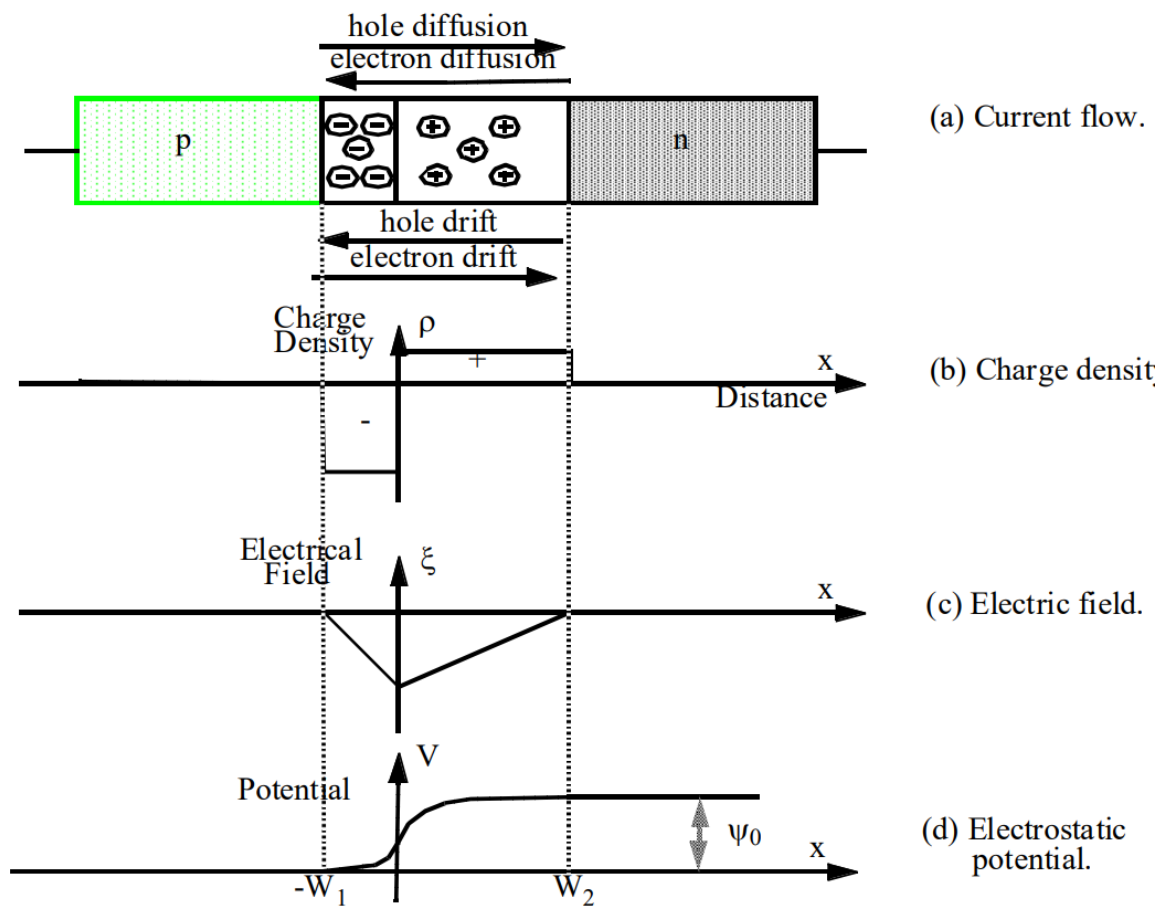
In summary...

### 20.1 Device: PN Junction and Diodes

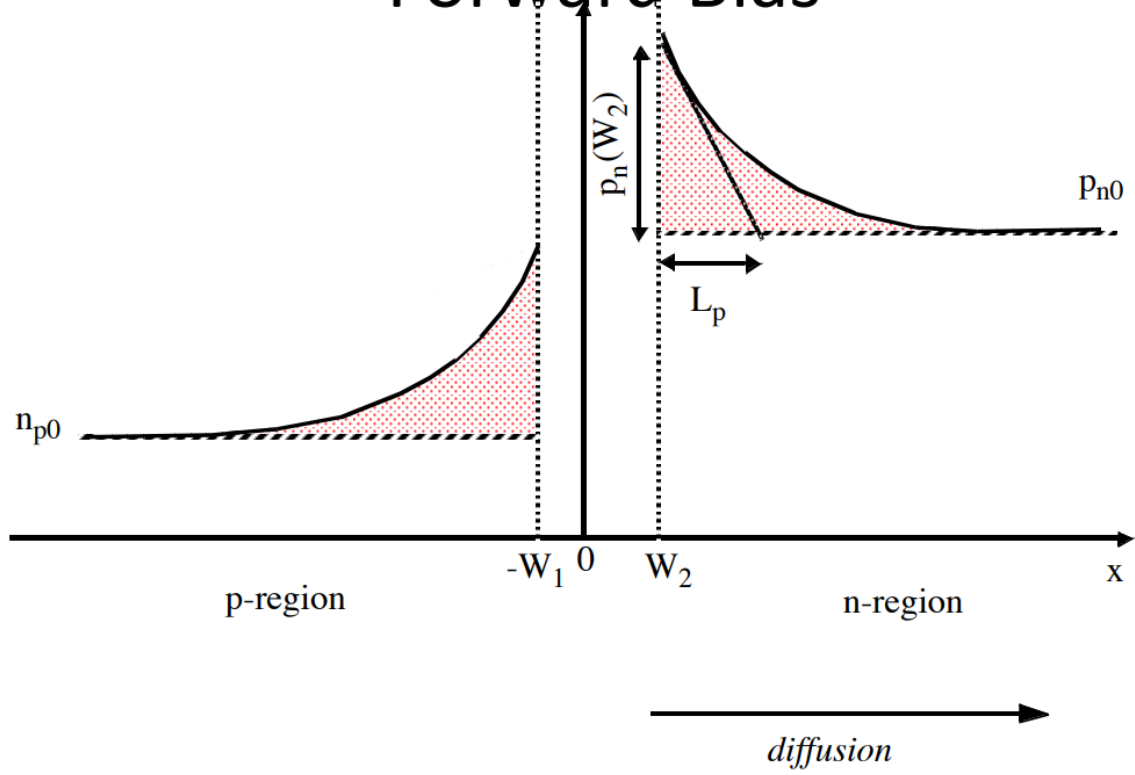
For a PN Junction:

- Forward bias (voltage on P-side  $>$  N-side) shrinks depletion region - diode allows diffusion current - lowers  $V_t$  in a MOS
- Reverse bias (voltage on N-side  $>$  P-side) expands depletion region - diode has minimal current - raises  $V_t$  in a MOS

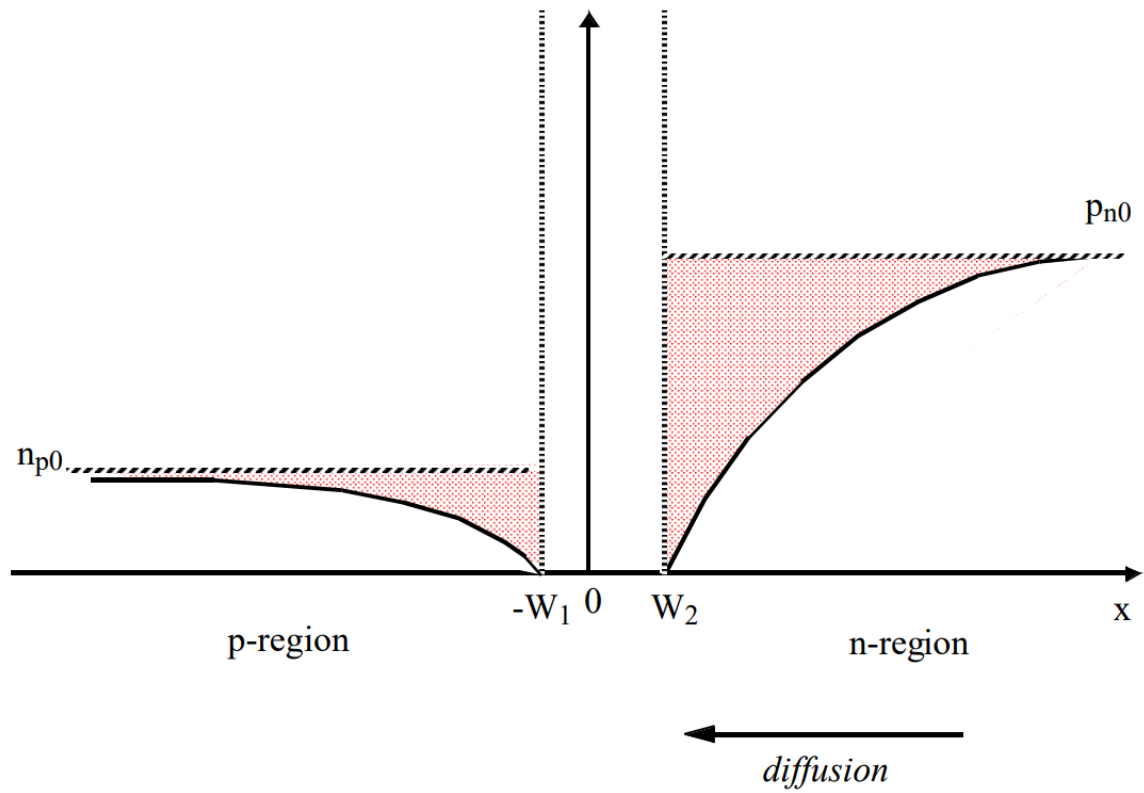
**Depletion Region**



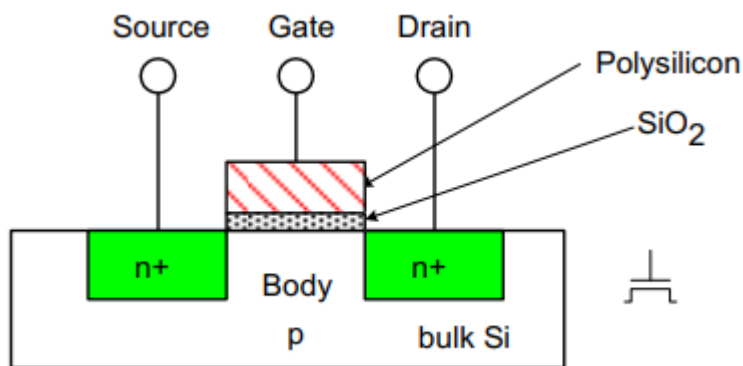
# Forward Bias

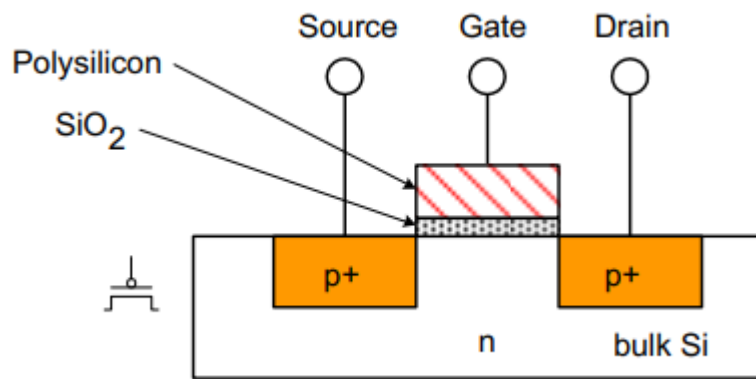


# Reverse Bias



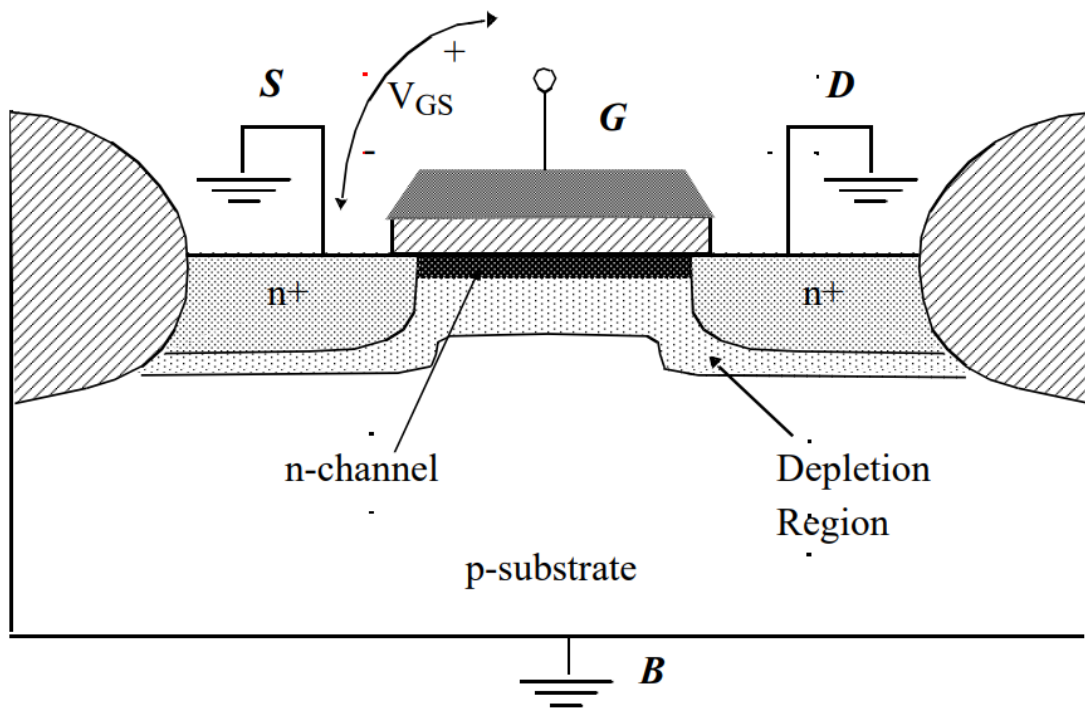
## 20.2 Device: MOS





Threshold Voltage

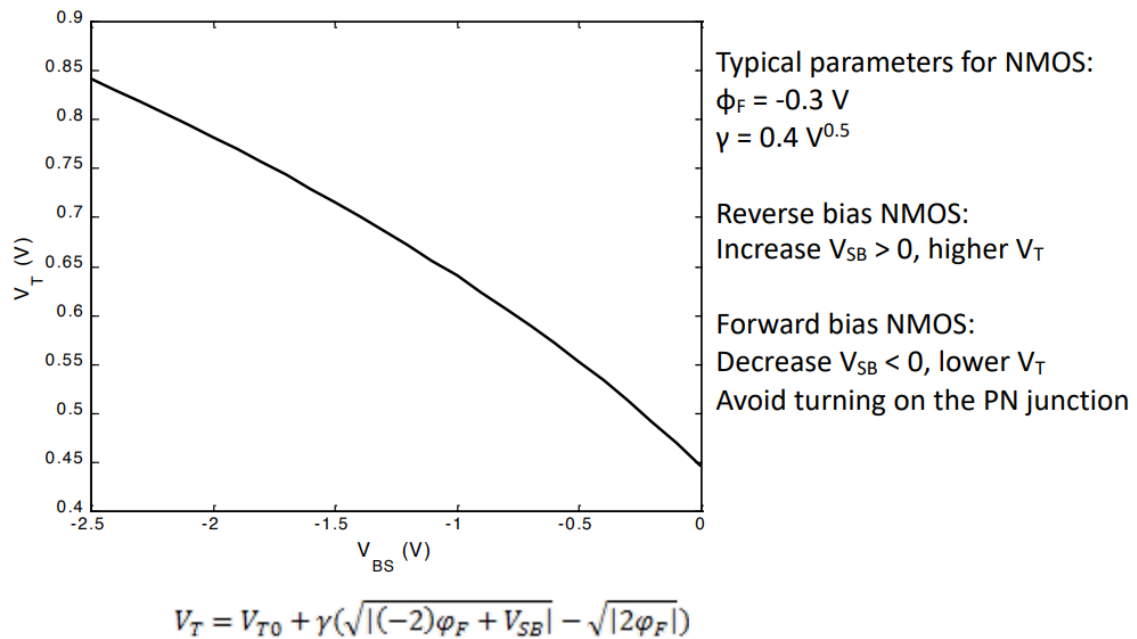
# Threshold Voltage: Concept



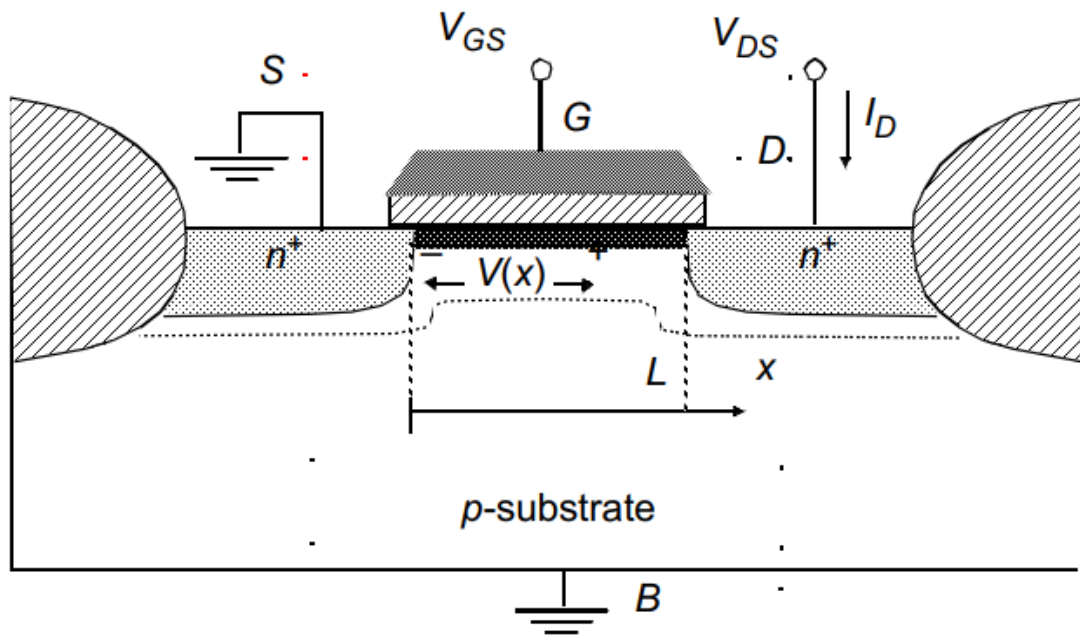
- $V_{GS} < 0$

- Accumulation of holes
- $0 < V_{GS} < V_T$ 
  - Depletion: repel mobile holes
  - Inversion: accumulation of electrons
- $V_{GS} > V_T$ 
  - Strong inversion: surface is as strongly n-type as the substrate is p-type

### Body Effect



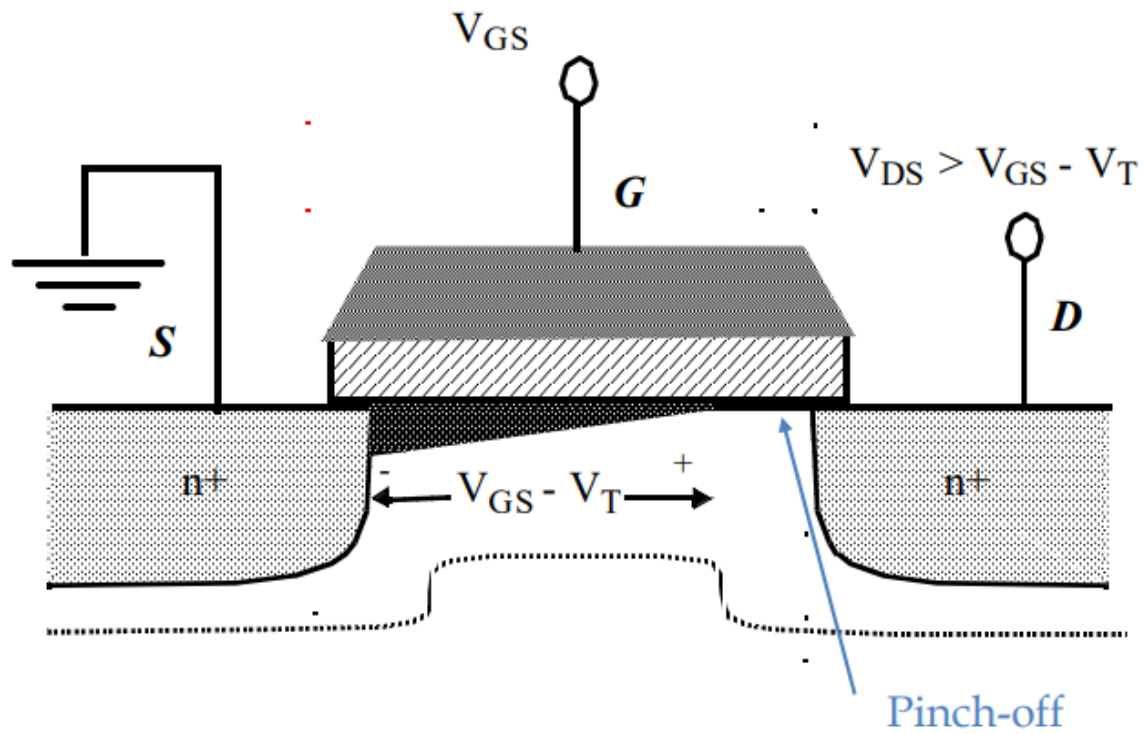
# Transistor in Linear



MOS transistor and its bias conditions



# Transistor in Saturation



# Current-Voltage Relations

## Long-Channel Device

**Linear Region:  $V_{DS} \leq V_{GS} - V_T$**

$$I_D = k'_n \frac{W}{L} \left( (V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right)$$

with

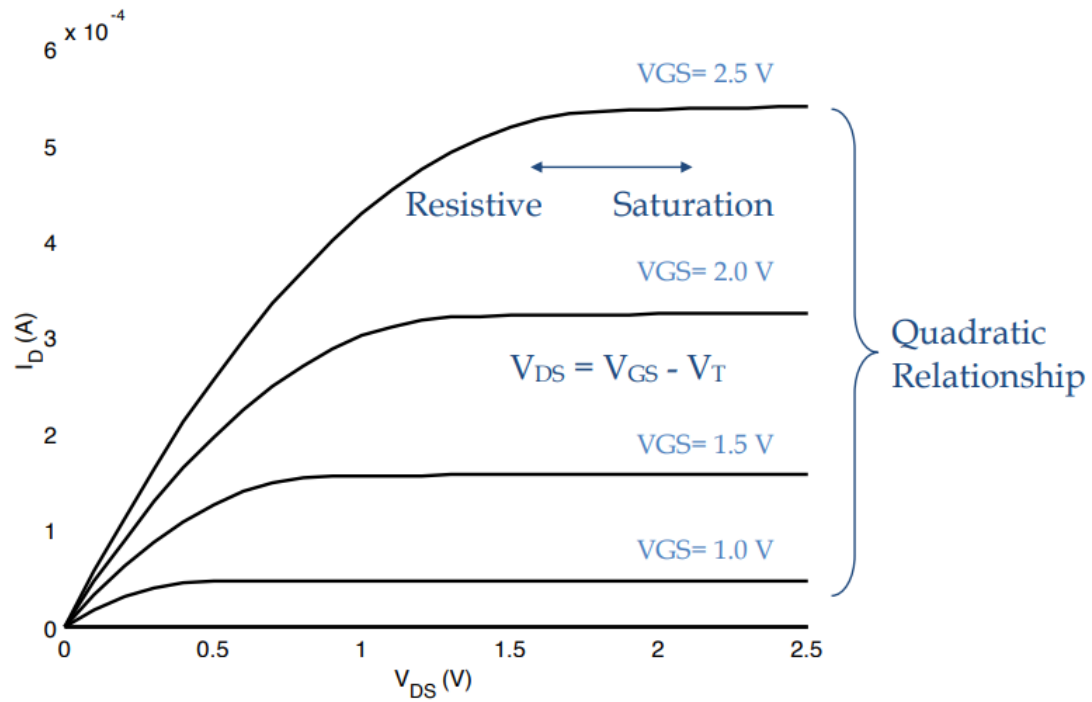
$$k'_n = \mu_n C_{ox} = \frac{\mu_n \epsilon_{ox}}{t_{ox}} \quad \text{Process Transconductance Parameter}$$

**Saturation Mode:  $V_{DS} \geq V_{GS} - V_T$**

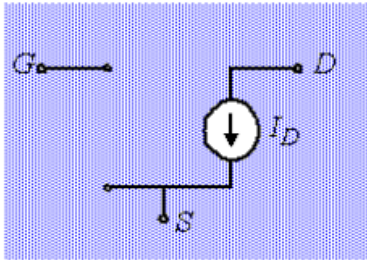
$$I_D = \frac{k'_n W}{2 L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

Channel Length Modulation  
↙

# Current-Voltage Relations



# A model for manual analysis



$$V_{DS} > V_{GS} - V_T$$

$$I_D = \frac{k'_n W}{2 L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

$$V_{DS} < V_{GS} - V_T$$

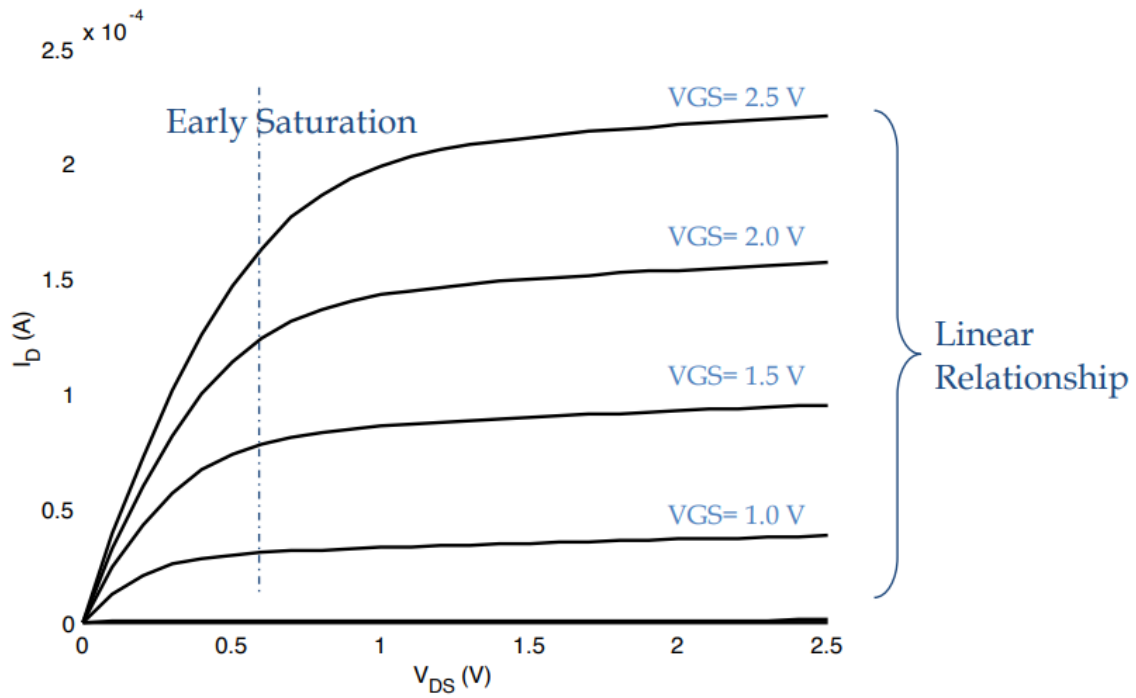
$$I_D = k'_n \frac{W}{L} \left( (V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right)$$

with

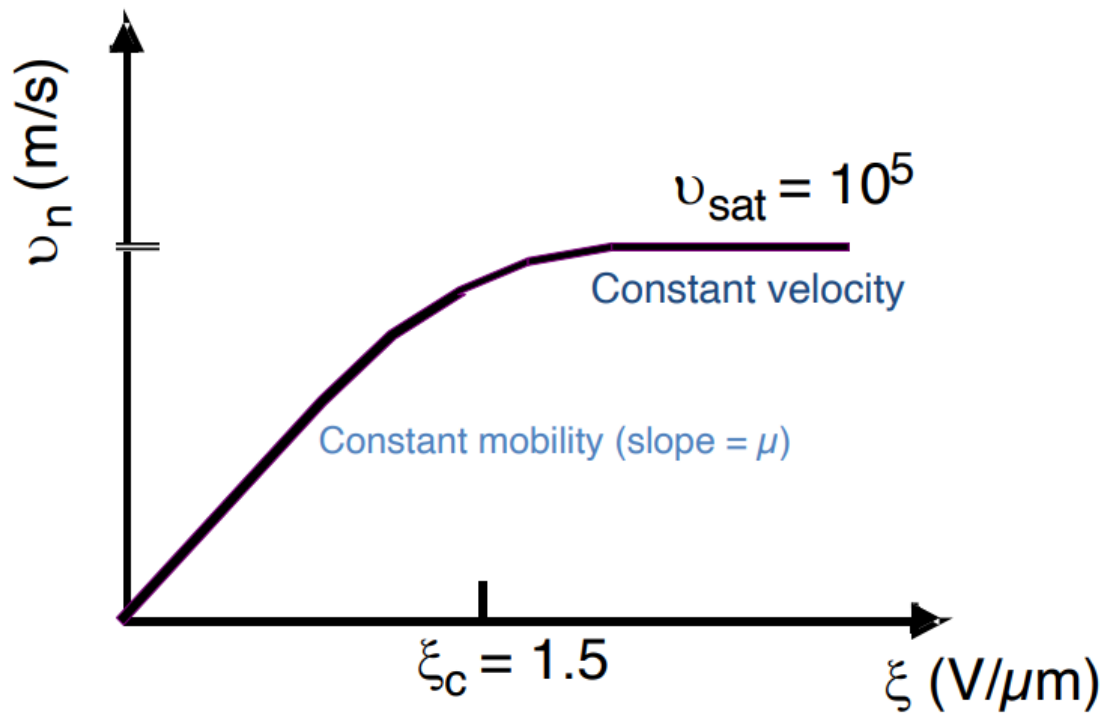
$$V_T = V_{T0} + \gamma (\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

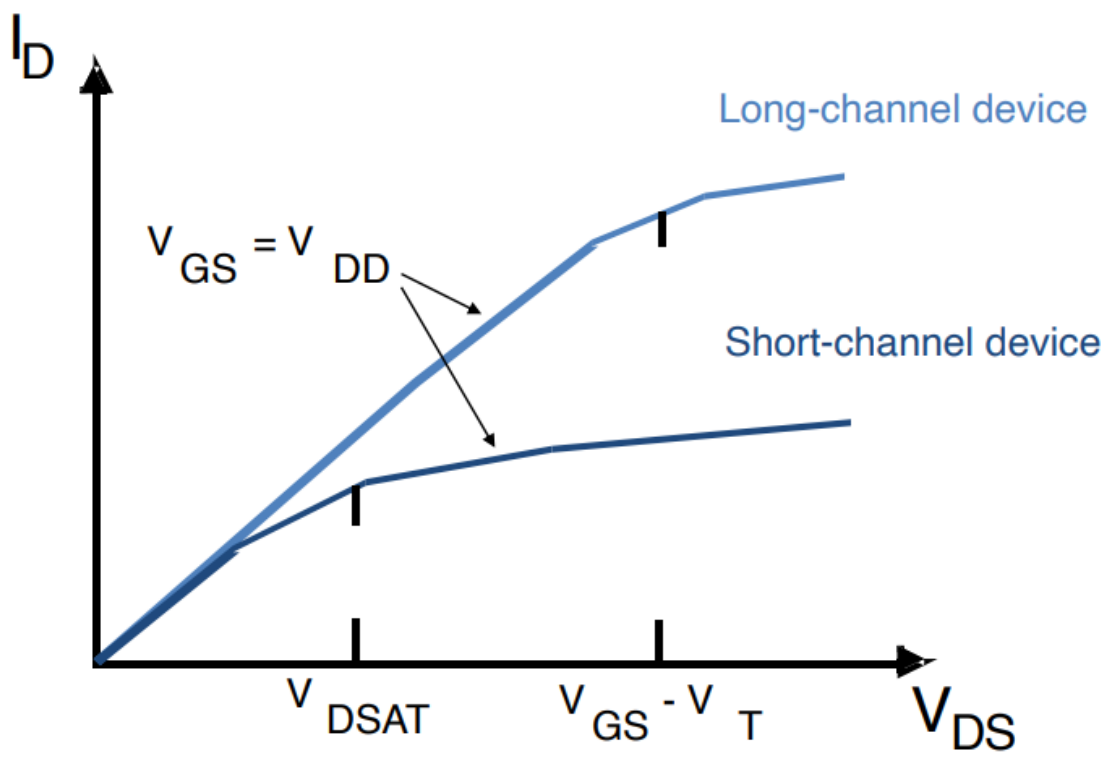
# Current-Voltage Relations

## The Deep-Submicron Era

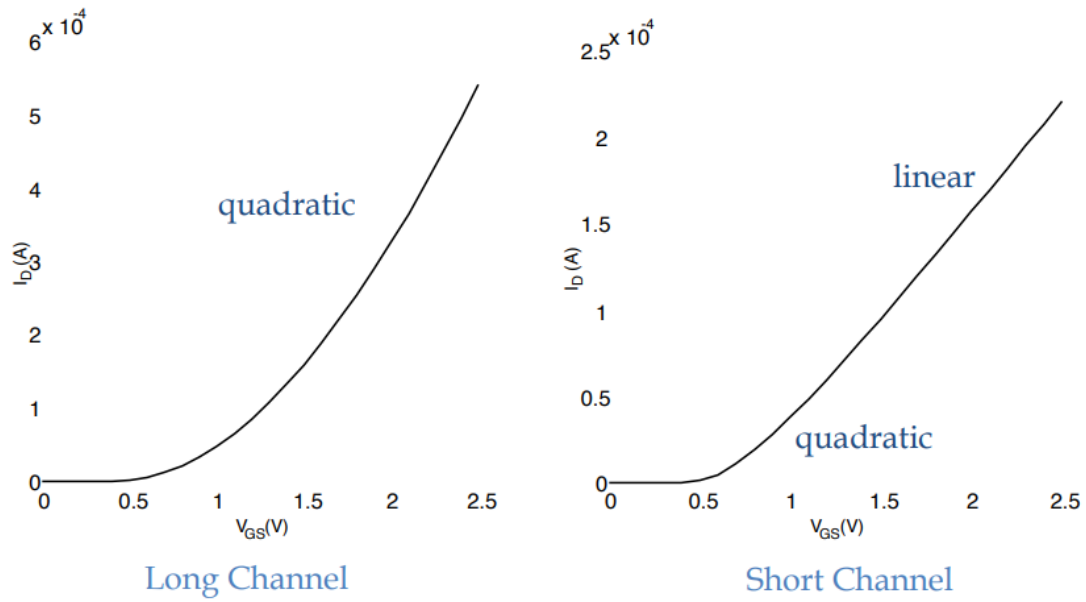


# Velocity Saturation



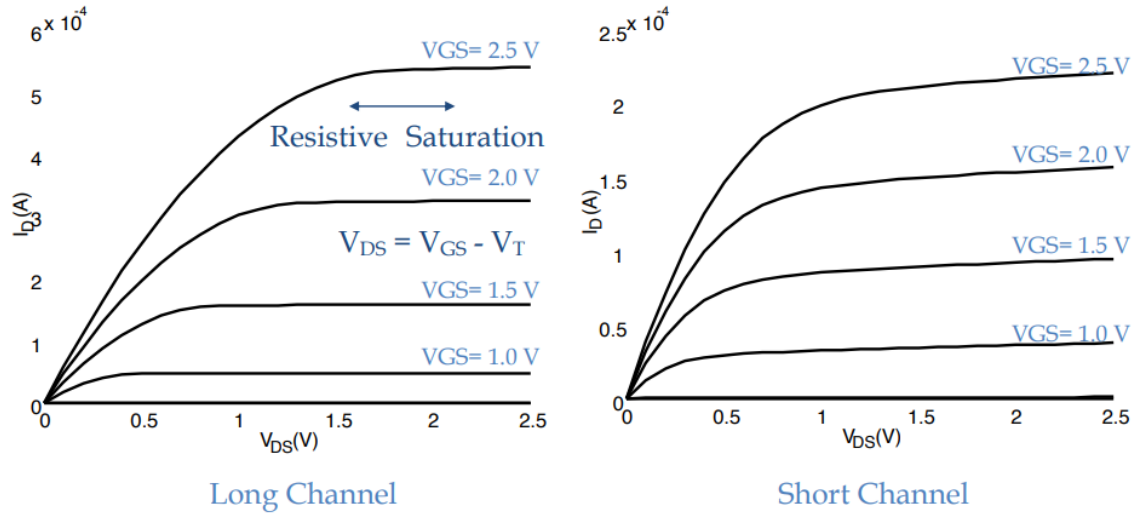


# $I_D$ versus $V_{GS}$

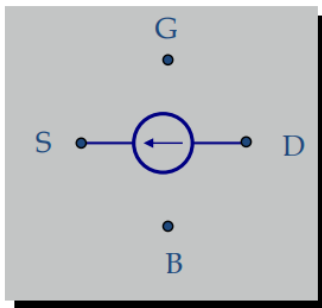




# $I_D$ versus $V_{DS}$



## A unified model for manual analysis



$$I_D = 0 \text{ for } V_{GT} \leq 0$$

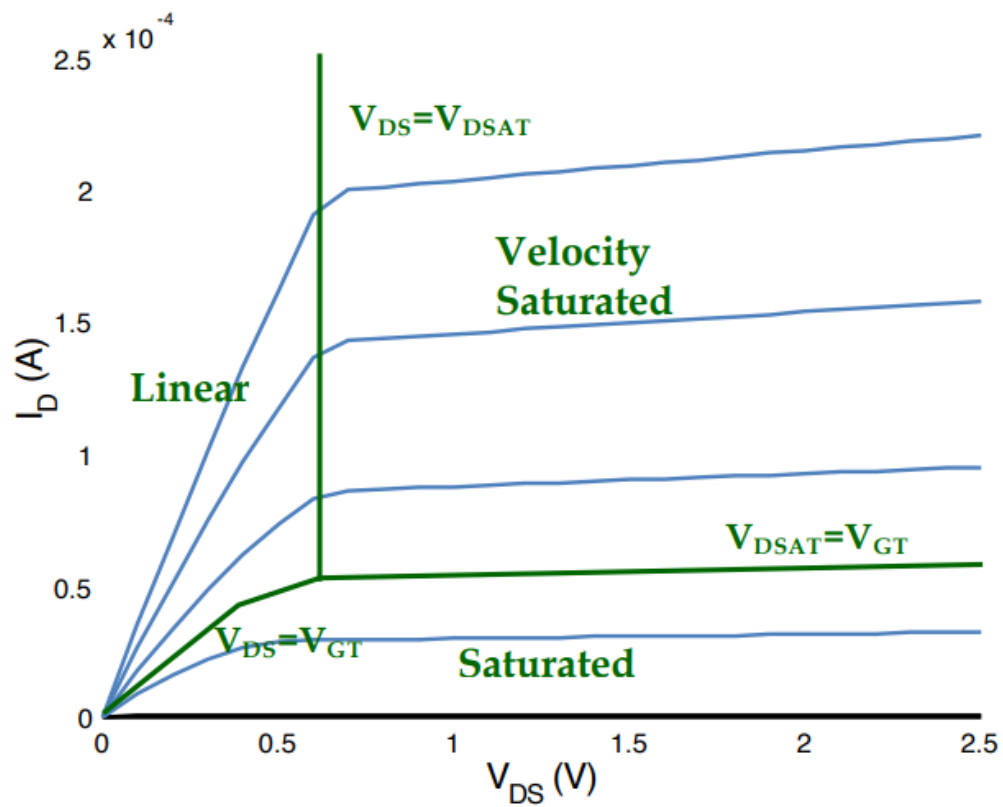
$$I_D = k' \frac{W}{L} \left( V_{GT} V_{min} - \frac{V_{min}^2}{2} \right) (1 + \lambda V_{DS}) \text{ for } V_{GT} \geq 0$$

$$\text{with } V_{min} = \min(V_{GT}, V_{DS}, V_{DSAT}),$$

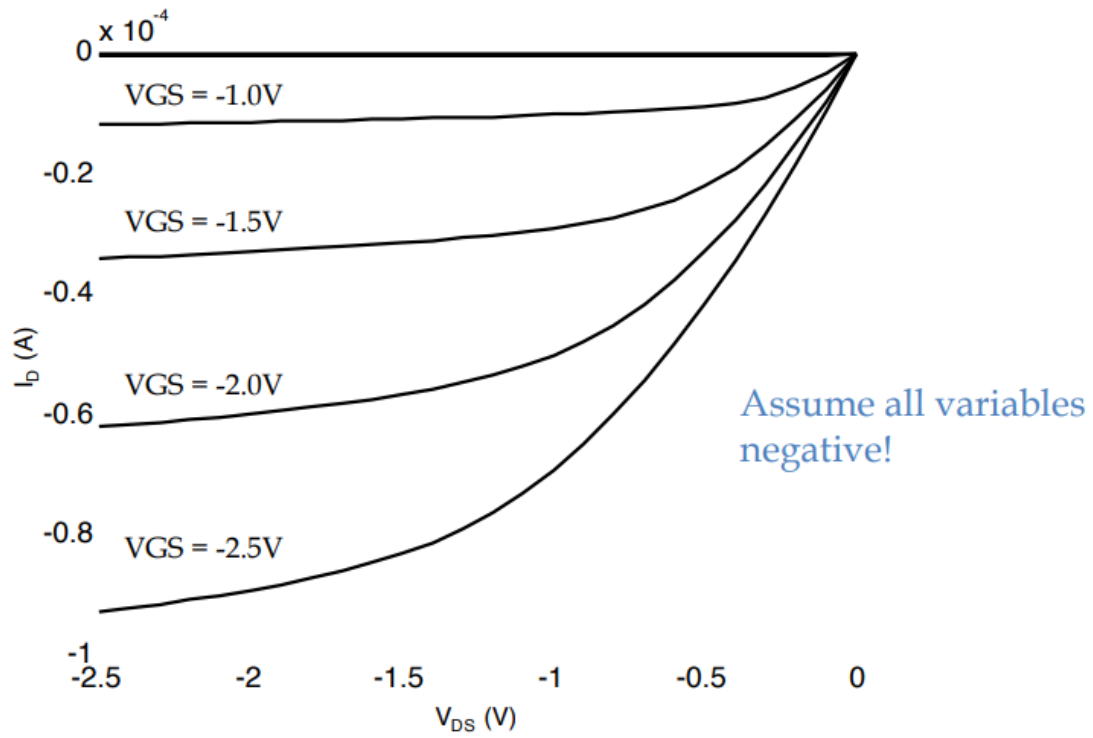
$$V_{GT} = V_{GS} - V_T,$$

$$\text{and } V_T = V_{T0} + \gamma (\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

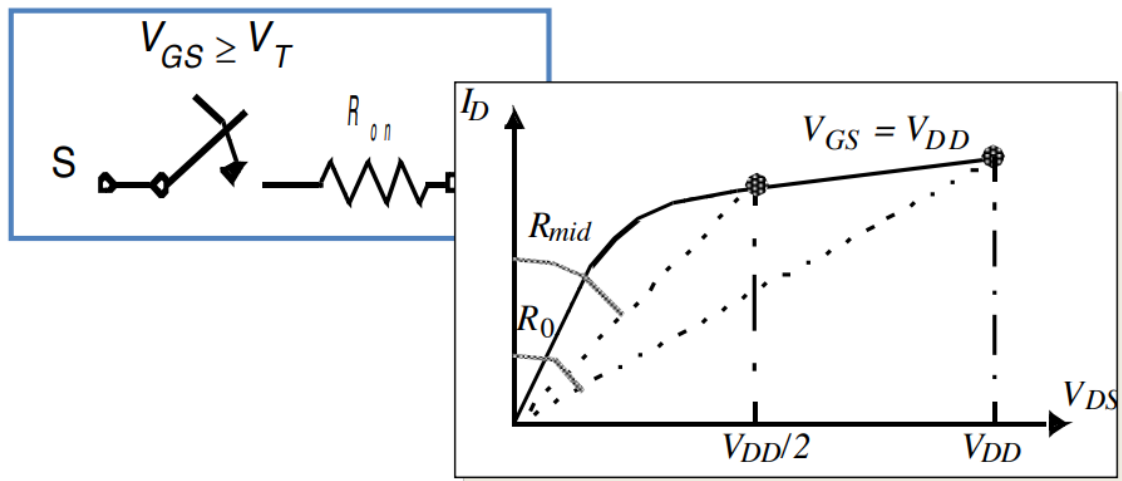
# Simple Model versus SPICE



# A PMOS Transistor

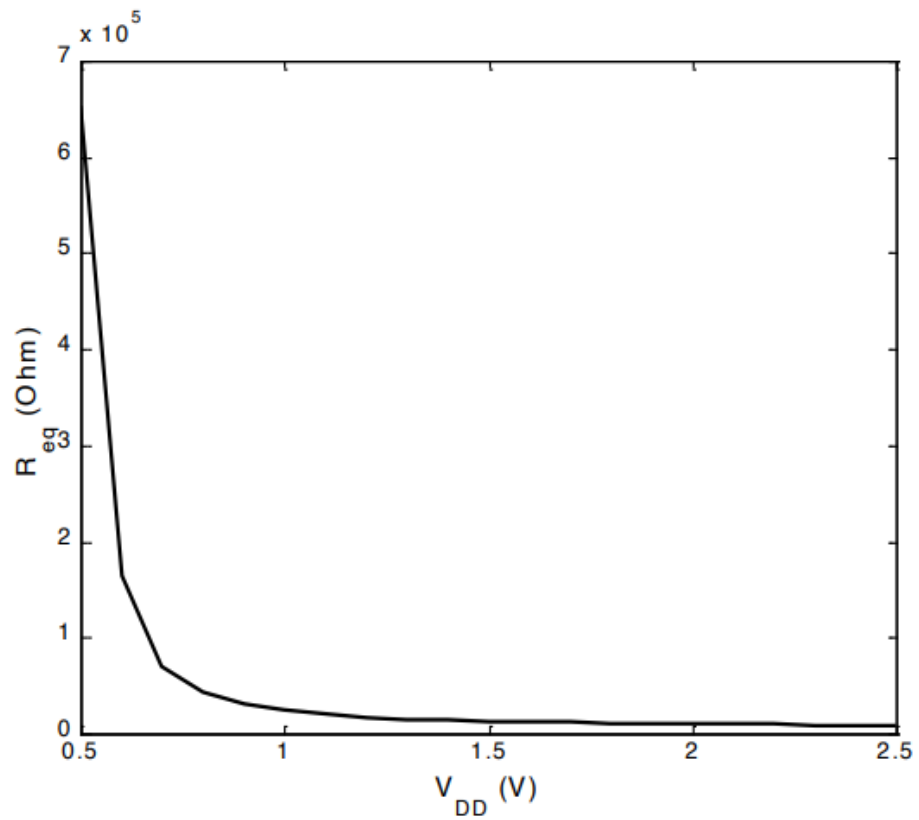


# The Transistor as a Switch

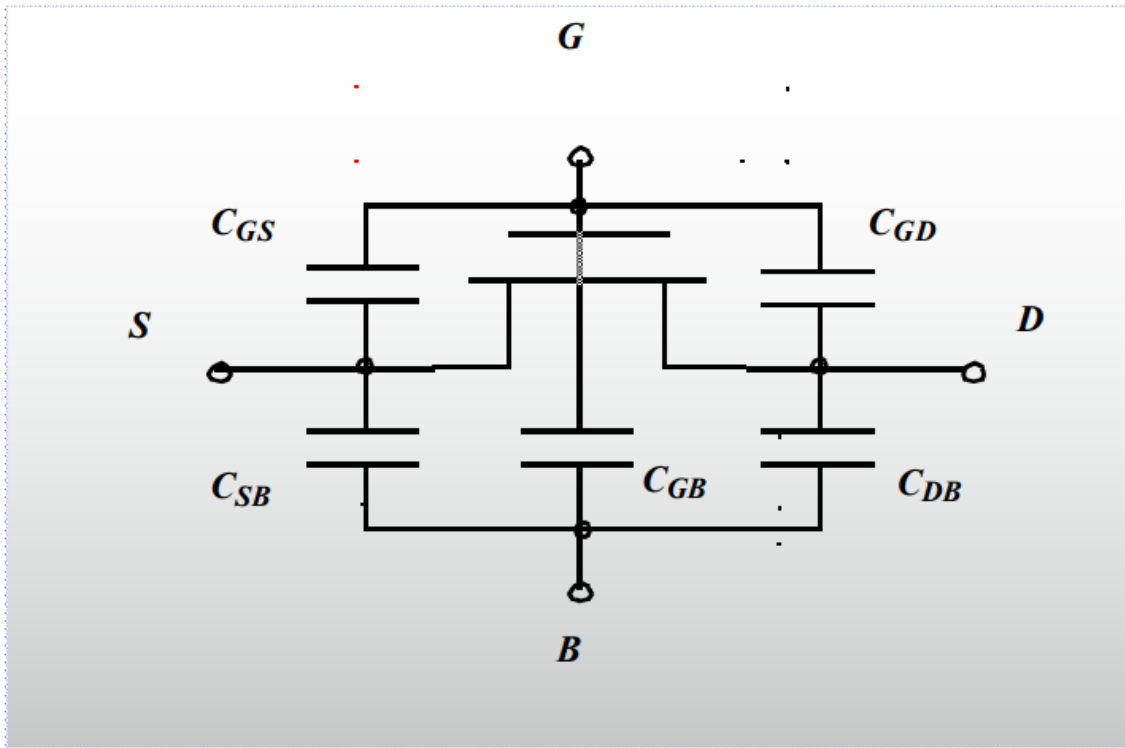


$$R_{eq} = \frac{1}{2} \left( \frac{V_{DD}}{I_{DSAT}(1 + \lambda V_{DD})} + \frac{V_{DD}/2}{I_{DSAT}(1 + \lambda V_{DD}/2)} \right) \approx \frac{3}{4} \frac{V_{DD}}{I_{DSAT}} \left( 1 - \frac{5}{6} \lambda V_{DD} \right)$$

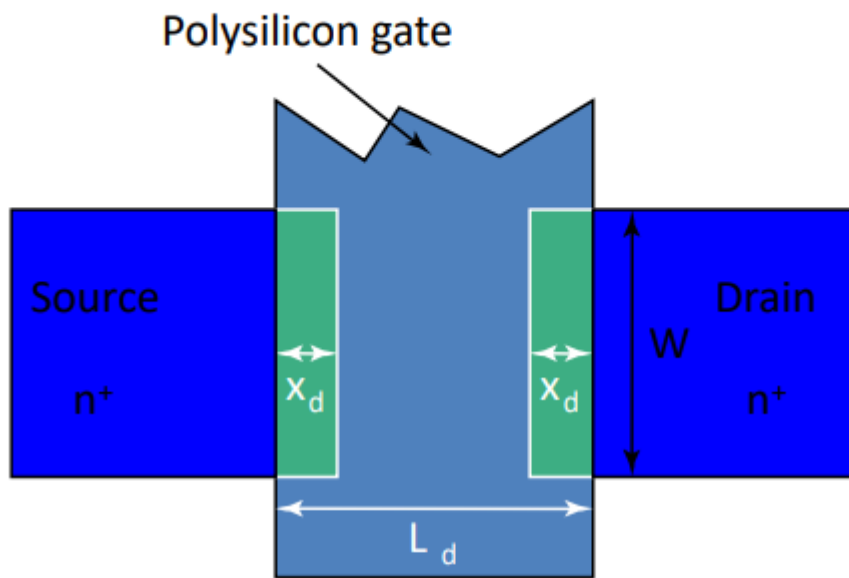
# The Transistor as a Switch



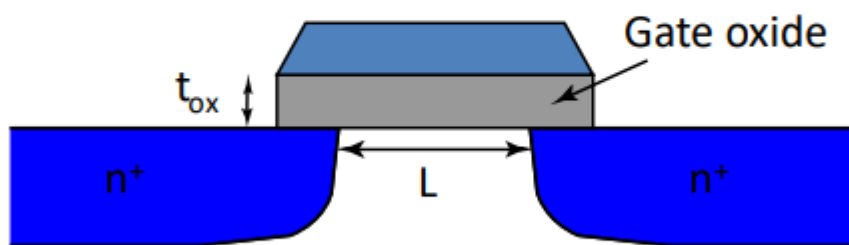
## MOS Parasitic Capacitances



# Gate Overlap Capacitance

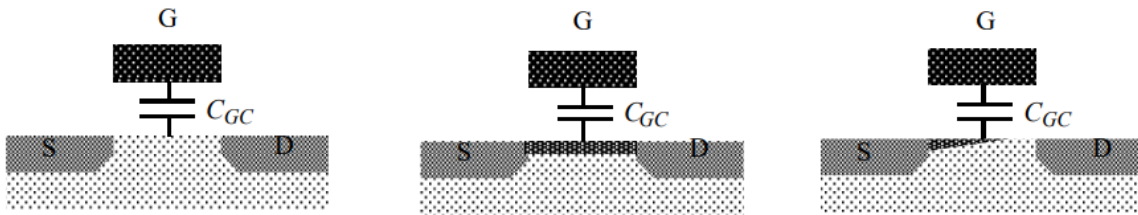


**Top view**



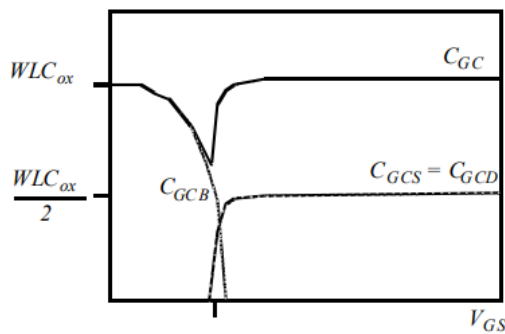
**Cross section**

# Gate-to-Channel Capacitance

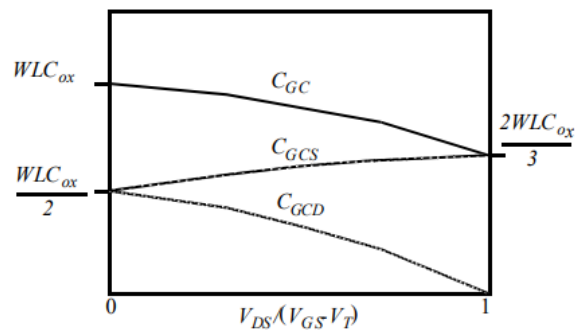


Operation Region	$C_{gb}$	$C_{gs}$	$C_{gd}$
Cutoff	$C_{ox}WL_{eff}$	0	0
Triode	0	$C_{ox}WL_{eff}/2$	$C_{ox}WL_{eff}/2$
Saturation	0	$(2/3)C_{ox}WL_{eff}$	0

## Gate Capacitance



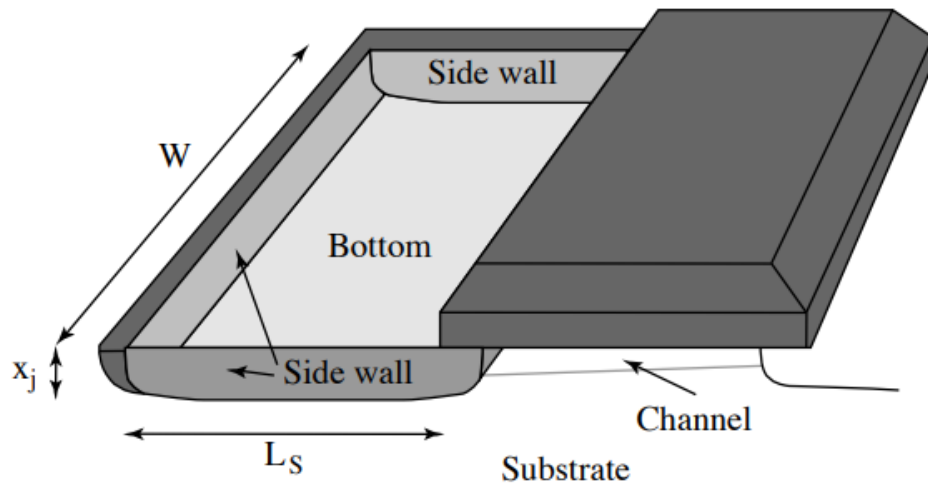
Capacitance as a function of  $V_{GS}$   
(with  $V_{DS} = 0$ )



Capacitance as a function of the  
degree of saturation



# Diffusion (Junction) Capacitance



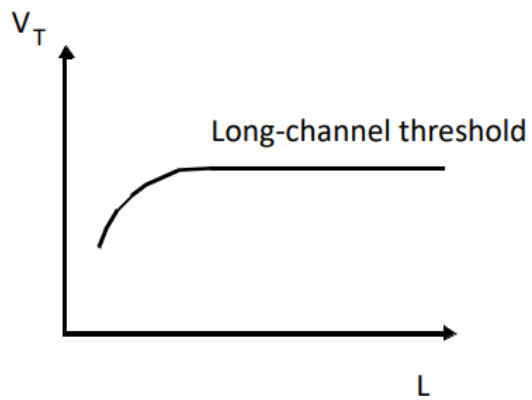
$$C_{diff} = C_{bottom} + C_{sw} = C_j \times AREA + C_{jsw} \times PERIMETER$$

$$= C_j L_S W + C_{jsw} (2L_S + W)$$

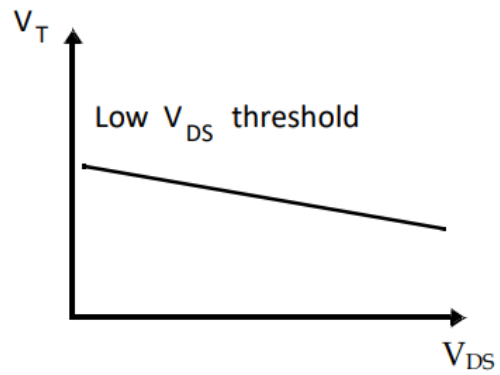
## Summary of Capacitances

- Parasitic capacitance of MOS transistor
  - (  $C_{GS}$  ): overlap, gate-to-channel (linear, saturation/velocity sat)
  - (  $C_{GD}$  ): overlap, gate-to-channel (linear)
  - (  $C_{GB}$  ): gate-to-channel (cutoff)
  - (  $C_{SB}$  ): bottom plate, side wall
  - (  $C_{DB}$  ): bottom plate, side wall, reverse-bias effect

# Threshold Variations

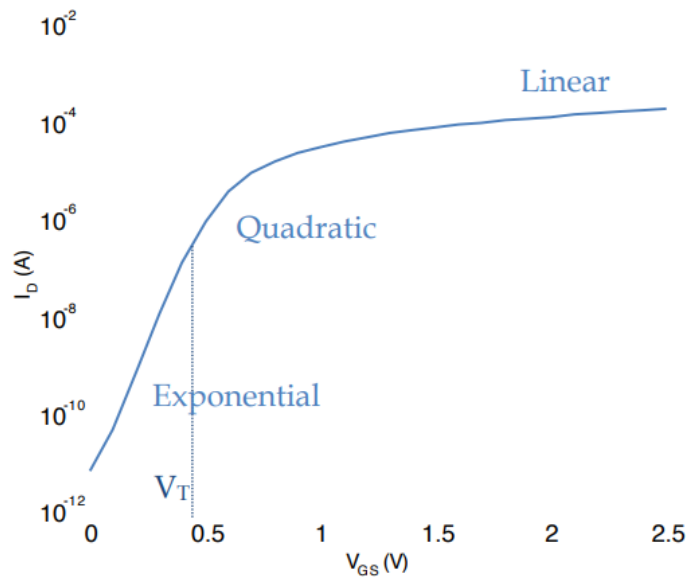


Threshold as a function of the length (for low  $V_{DS}$ )



Drain-induced barrier lowering (for low  $L$ )

# Sub-Threshold Conduction



$$I_D \sim I_0 e^{\frac{qV_{GS}}{nkT}}, \quad n \approx 1.5$$

## The Slope Factor

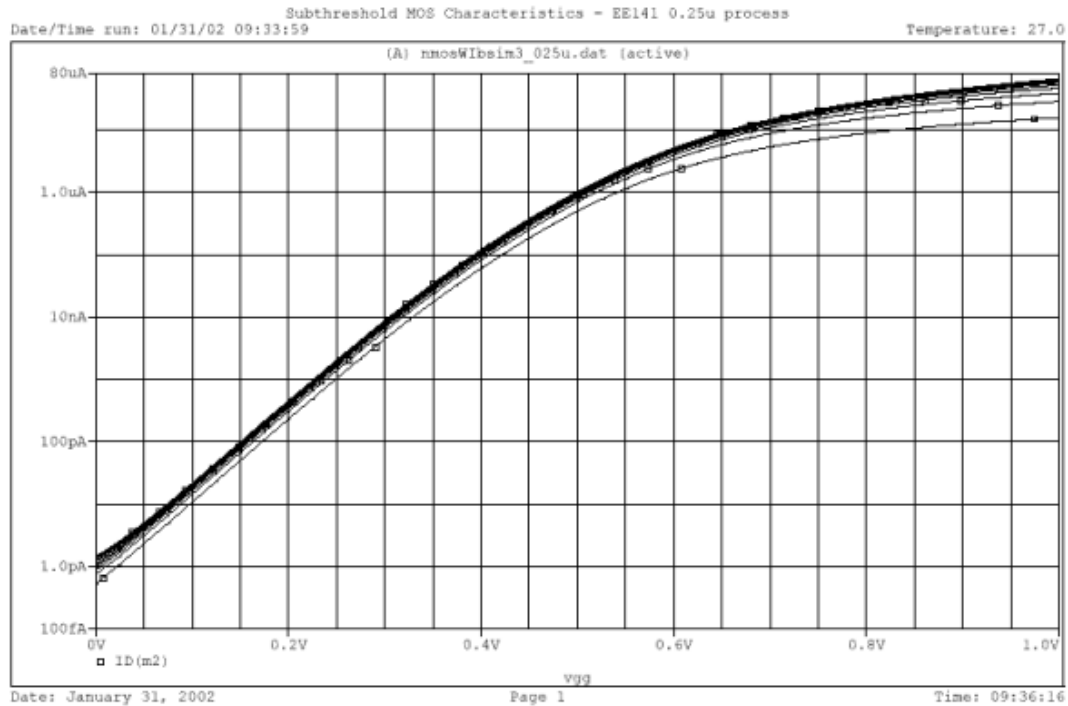
S is  $\Delta V_{GS}$  for  $I_{D2}/I_{D1} = 10$

$$S = n \left( \frac{kT}{q} \right) \ln(10)$$

Typical values for S:  
60 .. 100 mV/decade

# Sub-Threshold $I_D$ vs $V_{GS}$

$$I_D = I_0 e^{\frac{qV_{GS}}{nkT}} \left( 1 - e^{-\frac{qV_{DS}}{kT}} \right)$$

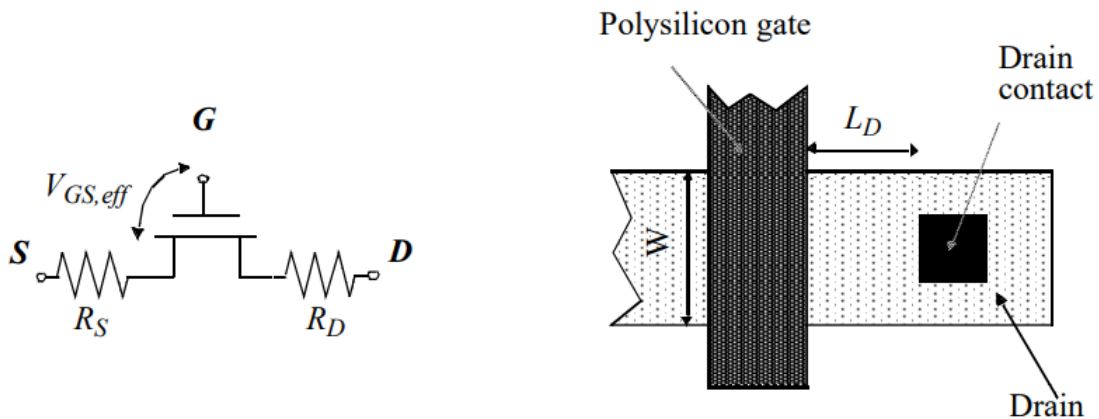


## Summary of Sub-threshold Conduction

- Exponential dependence on (  $V_{GS}$  )
- Slope factor
  - Higher slope factor (  $\rightarrow$  ) subthreshold curve bends up, much higher current when (  $V_{GS} = 0$  ) (more leakage when switched off)
  - Slope factor is a function of process parameter (  $n$  ) and temperature (  $T$  )
- (  $V_T$  ) effect
  - Lower (  $V_T$  ) (  $\rightarrow$  ) subthreshold curve shifts up, much higher current when (  $V_{GS} = 0$  ) (more leakage when switched off)

- ( $V_{T}$ ) is a function of many parameters, in particular ( $V_{SB}$ ) (body effect, reverse bias PN junction raises ( $V_{T}$ )) and ( $V_{DS}$ ) (drain-induced barrier lowering, higher ( $V_{DS}$ ) lowers ( $V_{T}$ ))

## Parasitic Resistances

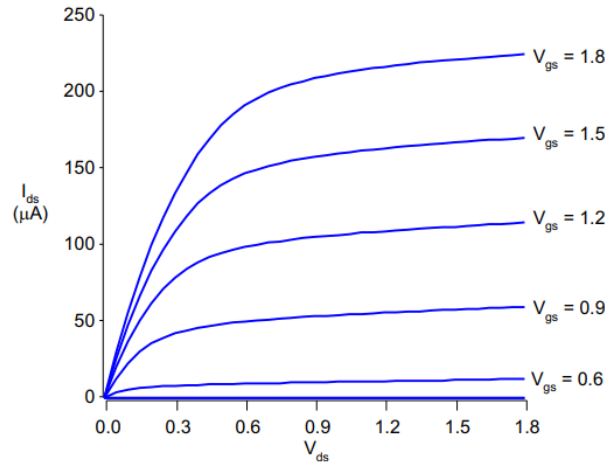
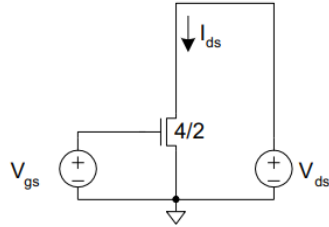


## Circuit Simulation

- DC analysis
  - Compute the DC (steady-state, i.e., time->infinity) voltage or current
  - Sweep a range of input values, obtain a collection of output values
- Transient analysis
  - Most frequently used
  - Simulates the operation of the circuit as time progresses
  - Determines propagation delay, rise and fall times, and power dissipation

# I-V Characteristics

- NMOS I-V



- 20.3 Device: MOS Fabrication**
- 20.4 CMOS Inverter: Static Operation**
- 20.5 CMOS Inverter: Dynamic Operation**
- 20.6 CMOS Inverter: Sizing and Energy**
- 20.7 CMOS Inverter: Scaling**
- 20.8 Static CMOS Gates**
- 20.9 Ratioed Logic**
- 20.10 Pass Transistor Logic**
- 20.11 Dynamic Logic**
- 20.12 Interconnects**
- 20.13 Latches and Registers**
- 20.14 Memories**
- 20.15 Memories: Peripherals**
- 20.16 Memories: Flash, SRAM, DRAM**

# 21 Interview & Problems

## 21.1 Interview

Concepts to know:

## 21.2 Problems

Common interview problems:

### 21.2.1 CMOS

### 21.2.2 Logic Design

### 21.2.3 Power

Q: Dynamic power dominates but why has static power consumption become increasingly important to deal with?

- Large transistor count - small leakage quickly get big when multiplied by billions of transistors
- Technology scaling - end of Dennard Scaling
  - Dennard Scaling suggested that power density remained constant at smaller transistor sizes - however the scaling has broken down at modern nodes
    - \* Scaling suggested VDD and VTh scales proportionally with feature size
  - VDD stopped scaling due to reliability
  - VTh stopped scaling as pushing it further down increases leakage
- Increased leakage currents
  - Subthreshold leakage - small threshold voltage leads to faster switching, but increases the leakage current even when transistor is OFF
  - Gate leakage - thin gate oxides in modern nodes lead to tunneling currents through the gate



- Junction leakage - small junction depths increase leakage at source/drain junctions

Q: How to reduce dynamic power?

Q: How to reduce static power?

Q: What caused the end of Dennard Scaling?

- VDD stopped scaling due to reliability
- VTh stopped scaling as pushing it further down increases leakage

#### **21.2.4 List of Questions - To be categorized...**

## References

Weste, Neil, and David Harris. 2010. *CMOS VLSI Design: A Circuits and Systems Perspective*. 4th ed. USA: Addison-Wesley Publishing Company.